

It's *time* we talk about LGADs

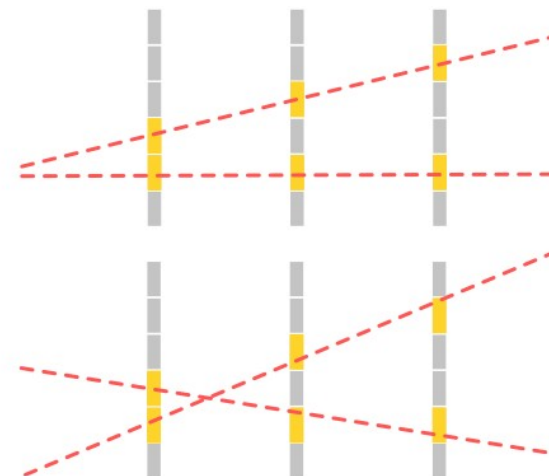
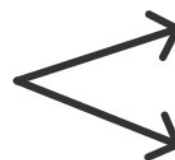
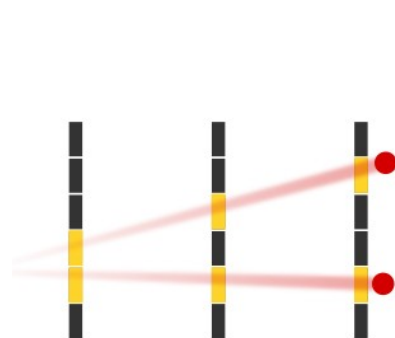
B. Raciti | FCC Meeting, 23rd April 2026

Why is timing important?

Experiments with *increasing number of collisions* per bunch-crossing (HL-LHC, FCC-ee...):

- track **timing** to complement spatial information
 - *timing layer* → add “timestamp” to each track
 - *4D tracking* → timing at each point along the track

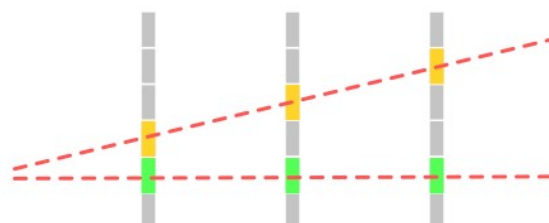
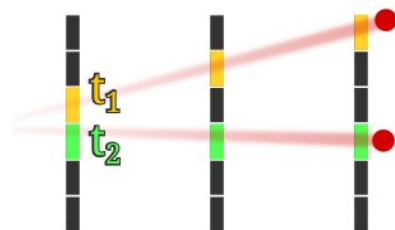
high occupancy regime



possibility 1

possibility 2

high occupancy regime
with 4D tracking

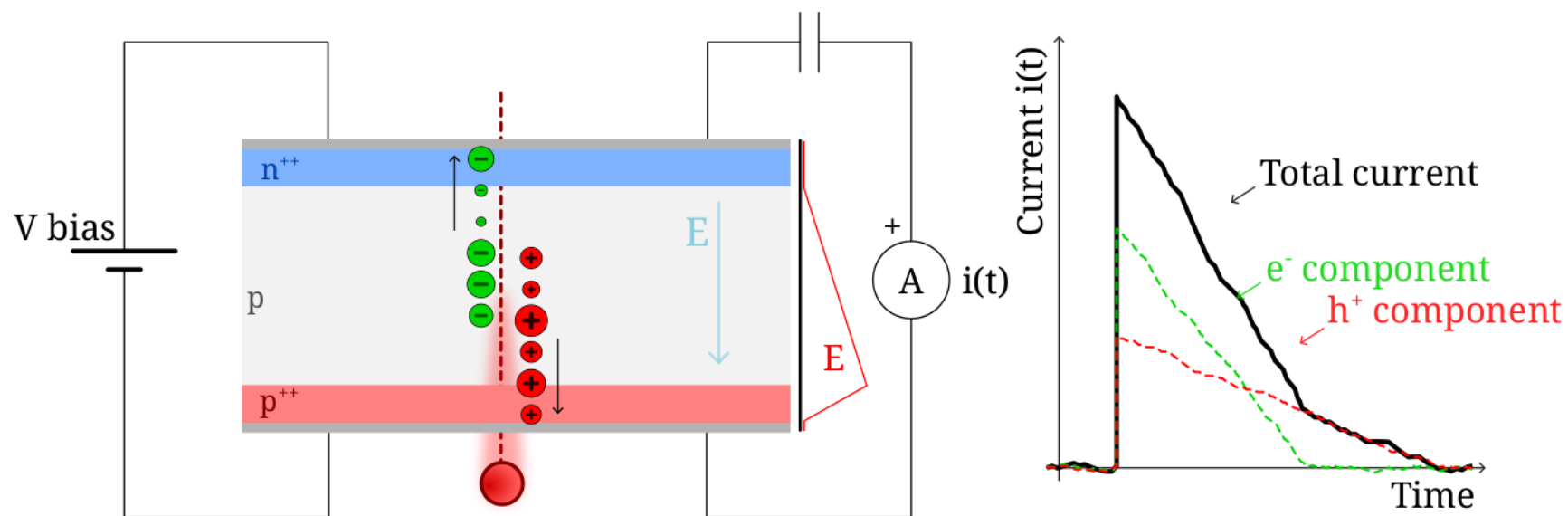


one obvious
option

What can we use for timing (in silicon)?

Precise timing requires **fast** and **intense** current signals:

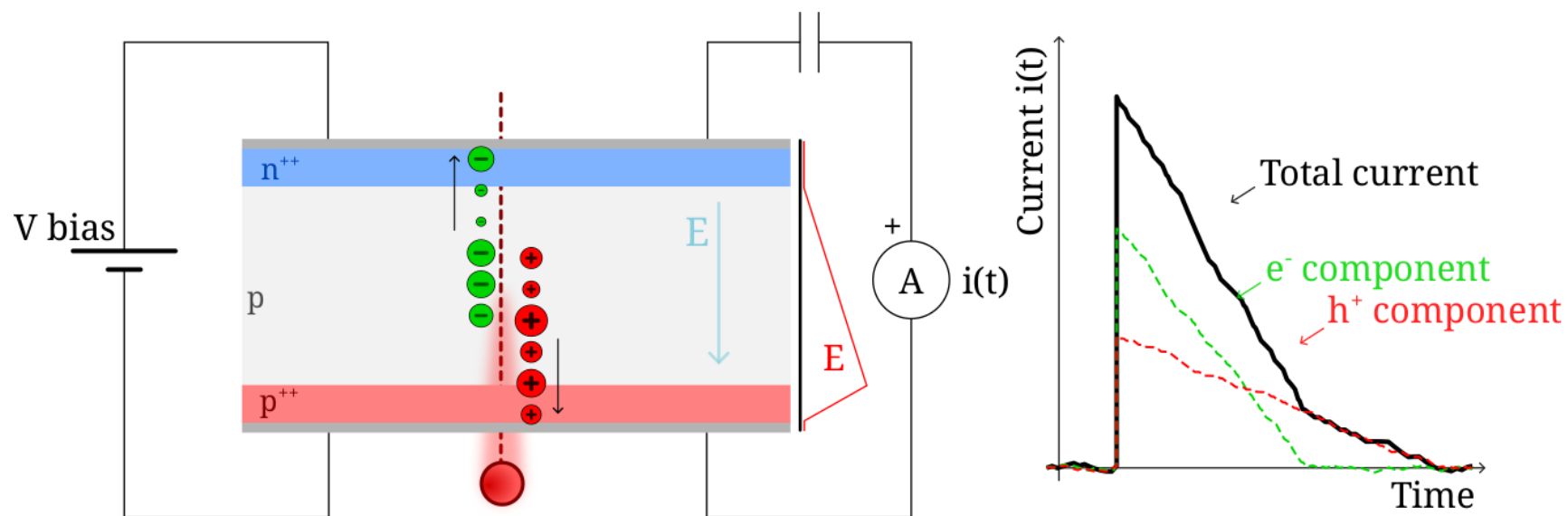
- more *charge* needed... thicker sensors?



What can we use for timing (in silicon)?

Precise timing requires **fast** and **intense** current signals:

- more *charge* needed... thicker sensors?
 - more drift time = slower signal → standard silicon sensors are not fit for the job



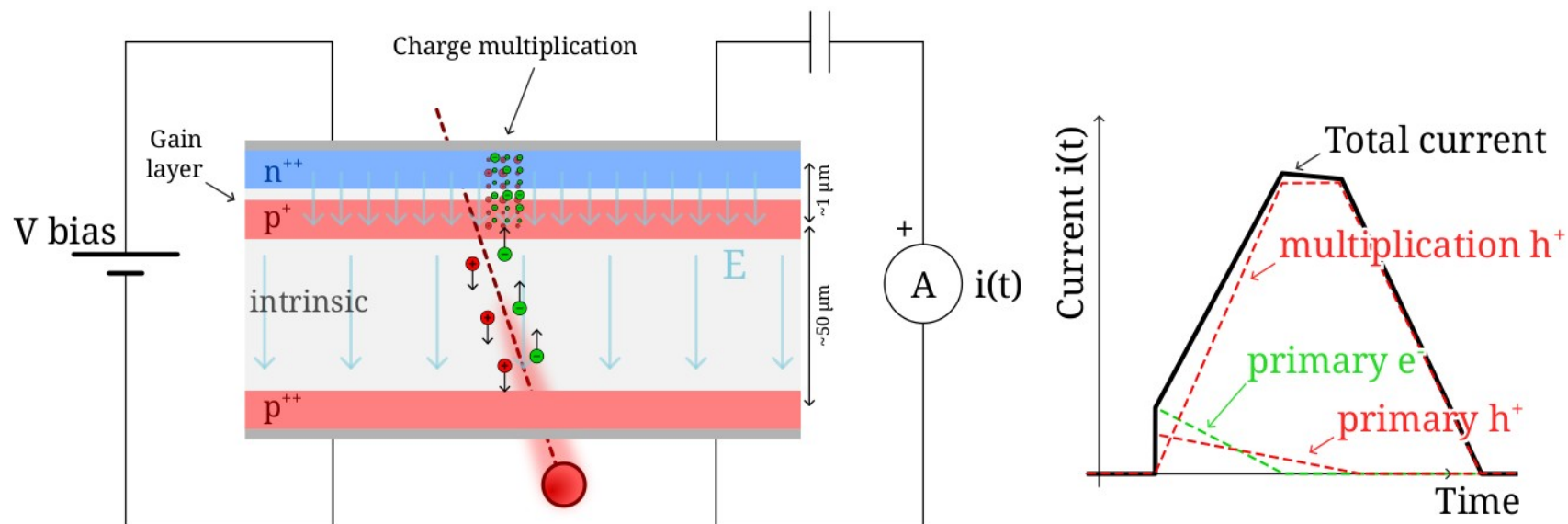
What is an LGAD?

Low Gain Avalanche Diodes (LGADs) are silicon sensor with **internal gain**:

- thinner sensors → smaller collection time = faster signals!

Charge multiplication achieved by **impact ionization** (avalanche process):

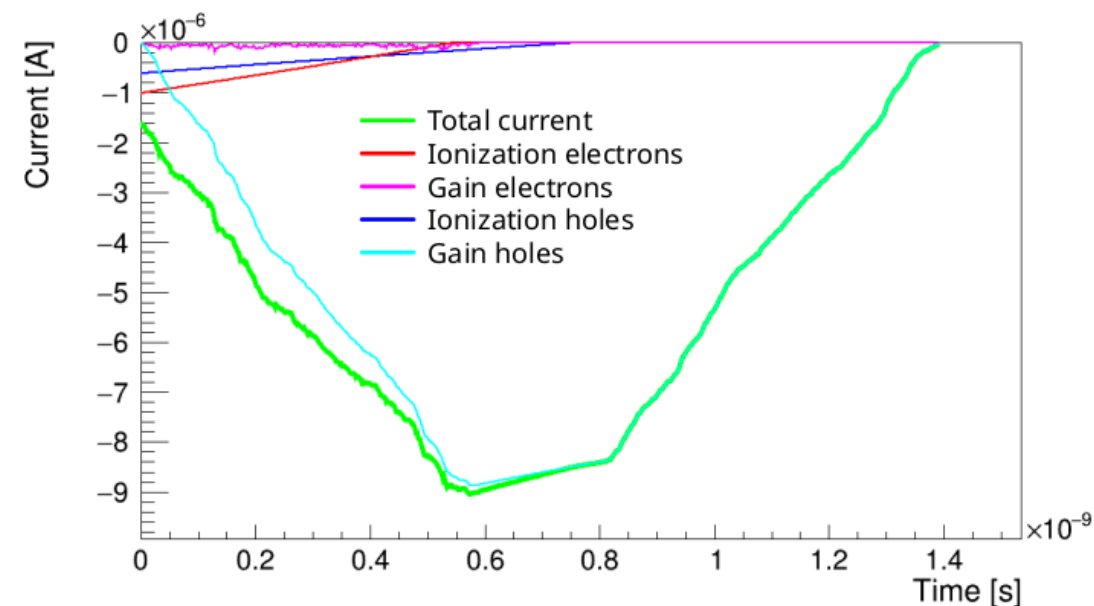
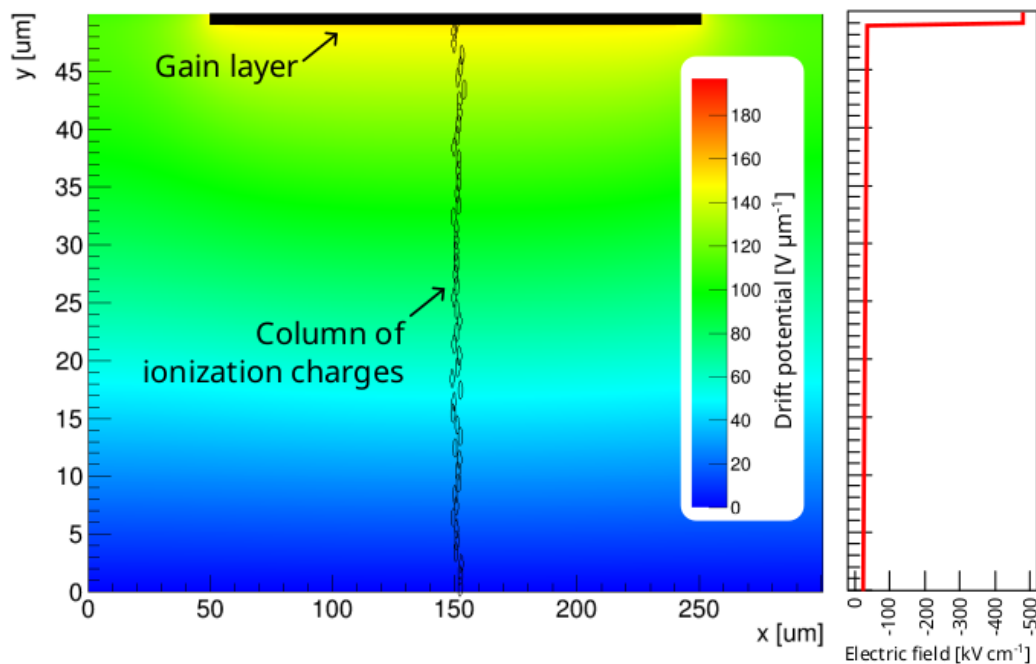
- additional p^+ doped layer ($N_A \sim 10^{16}$ atoms/cm³) under the n^{++} layer → $E \geq 300$ kV cm⁻¹
- **gain factor** of ~ 10 → better SNR without increasing shot noise and power consumption



How does an LGAD work?

E increases linearly along sensor thickness \rightarrow abrupt step at gain layer initiates **multiplication**:

- *ionization* e^-/h^+ contribute as for standard silicon sensors
- *gain* e^- are immediately collected, don't contribute to signal
- *gain* h^+ are produced by e^- reaching the high-field region in gain layer \rightarrow generate most of the signal



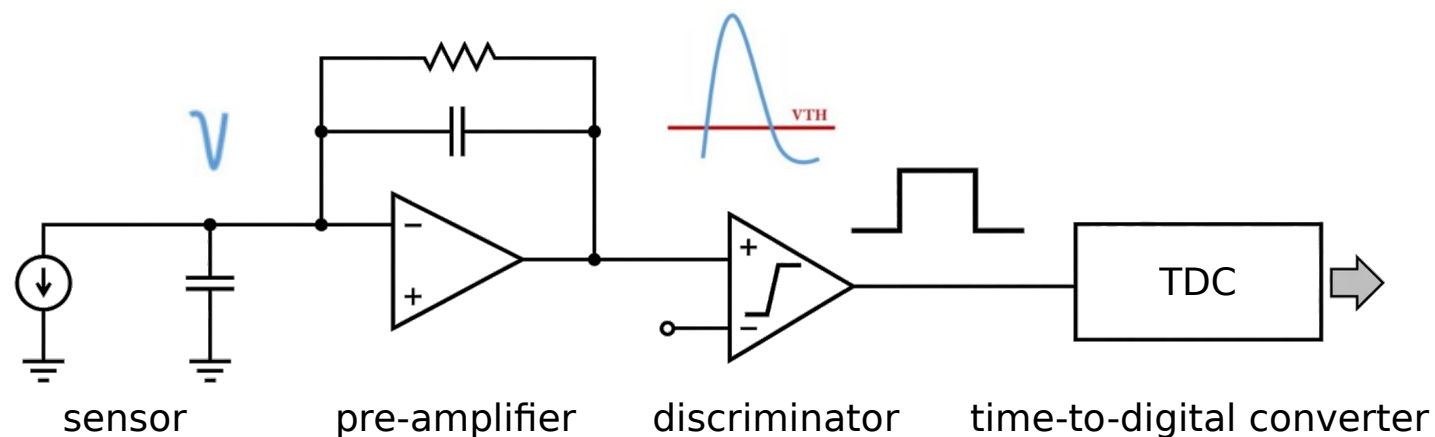
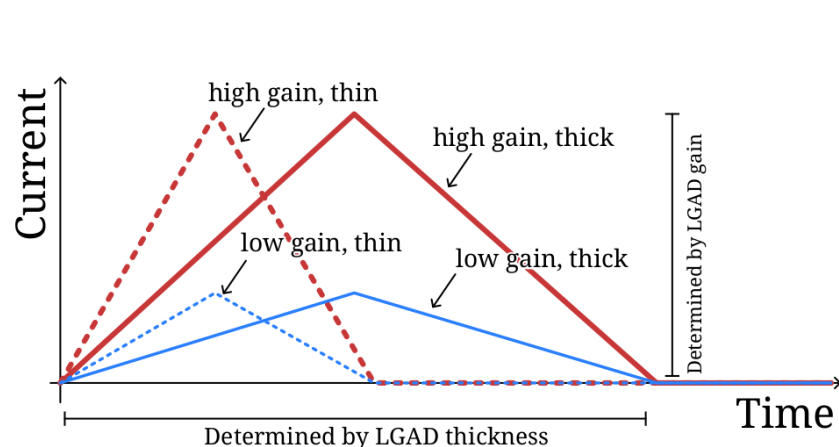
How does an LGAD work?

Looking at the signals **shape**:

- amplitude \propto *gain* and pulse duration \propto *thickness*
- rise time = e^- drift time through sensor thickness \rightarrow **slew rate**
 - *thinner sensors* = steeper signals, but increased junction **capacitance** affects time resolution (σ_t)
 - *high gain* increases slew rate, but impacts **SNR** and **power consumption** (higher V_{bias})

Signals are digitized in the TDC \rightarrow Time-of-Arrival (ToA) and Time-over-Threshold (ToT):

- $\sigma_t < 30$ ps with 50 μ m thick *standard* LGADs with 1.3 mm pitch
 - designs from IHEP and USTC
- target for HL-LHC, but **BIG** pixels!



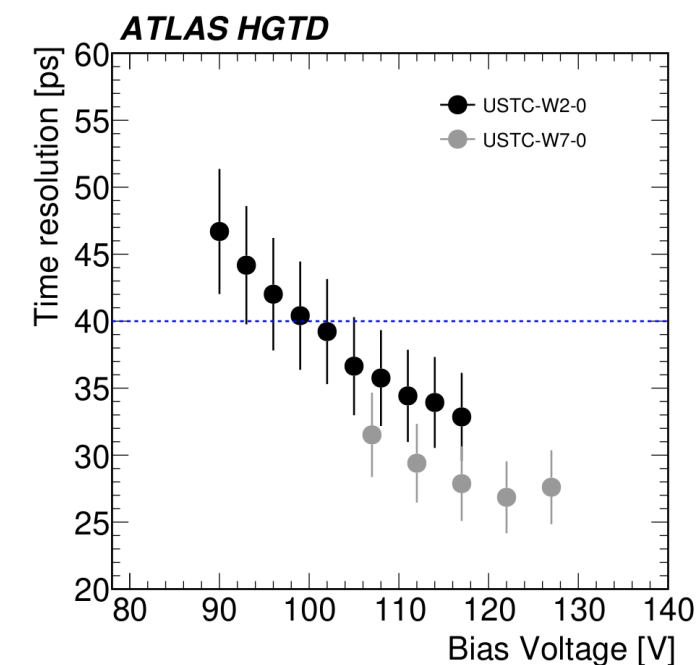
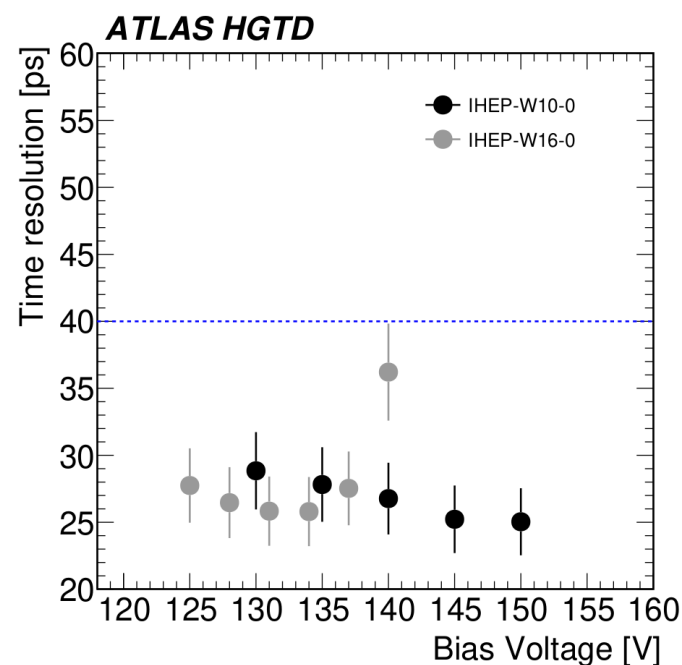
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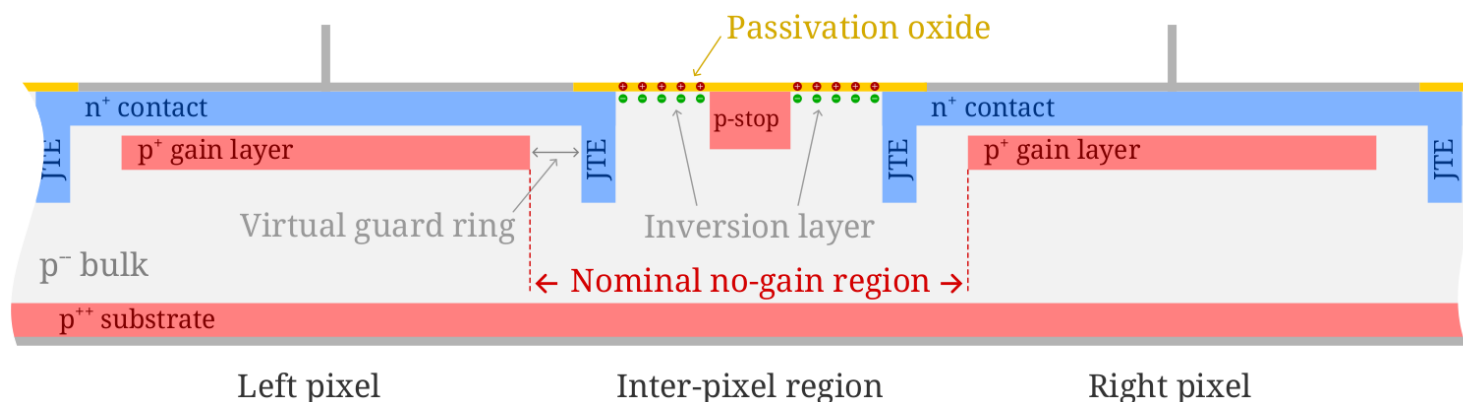
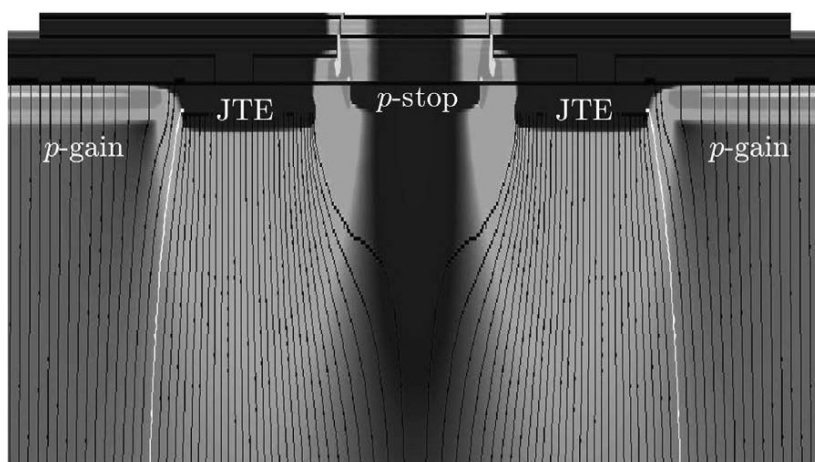


The problem: no-gain region

The **segmentation** of a *standard* LGAD requires:

- junction termination extension (JTE)
 - e^-/h^+ pairs generated between two pixels do not reach the gain layer \rightarrow lateral drift time impacts σ_t
 - reduces electric field at pixel boarder
- virtual guard ring
 - separation between gain layer and JTE, and avoids premature breakdown
- p-stop to isolate pixels:
 - avoiding formation of inversion layer under oxide shorting n^+ contacts

This leads to the *fill factor problem*.



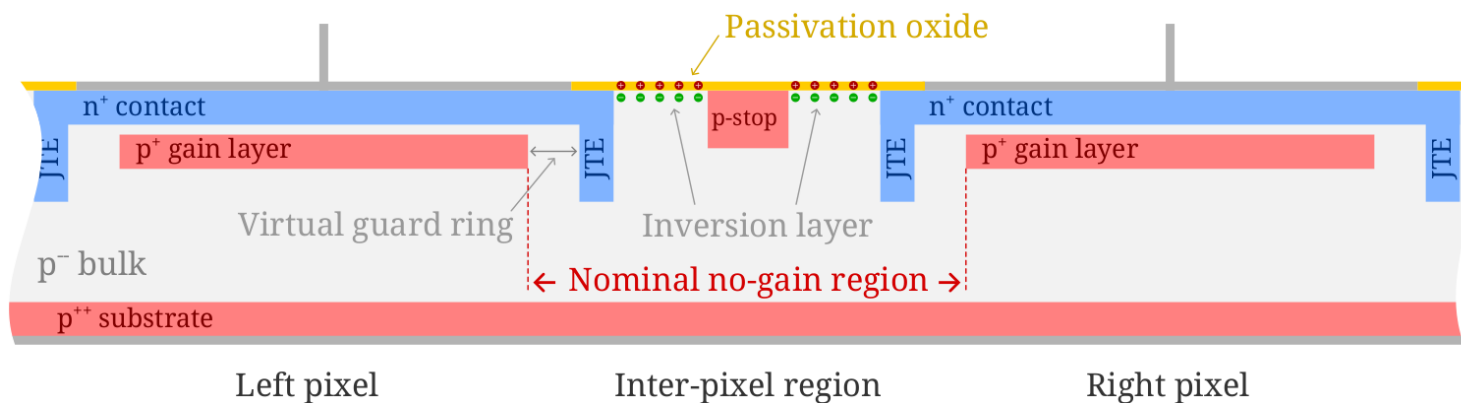
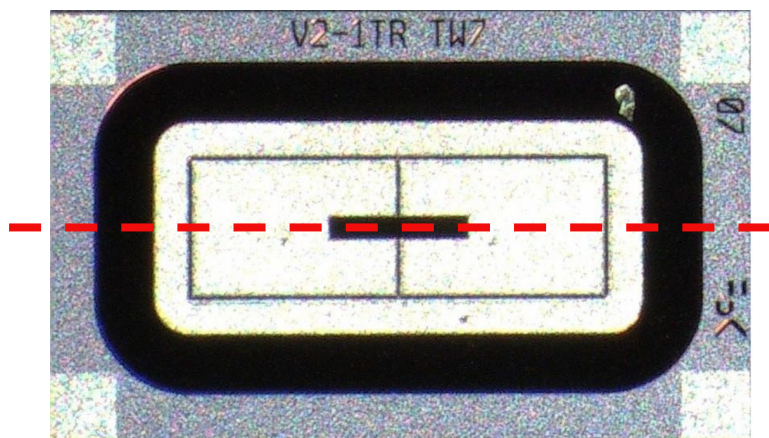
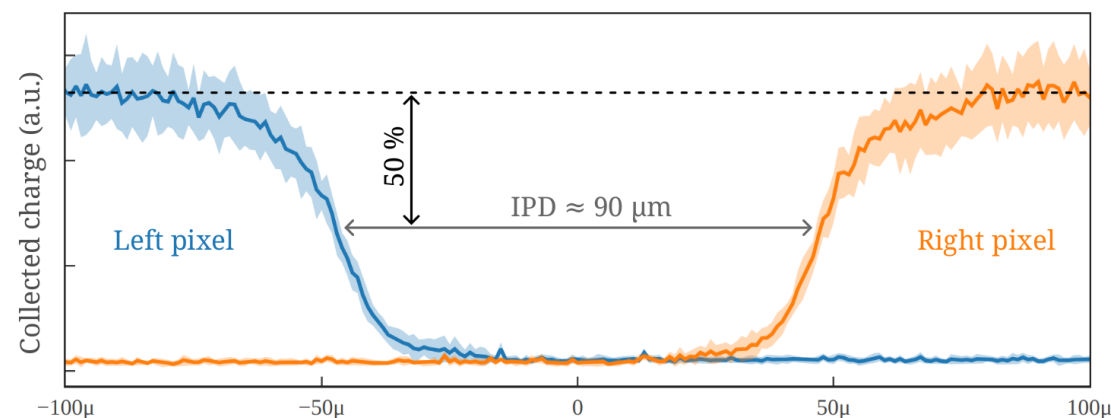
The problem: no-gain region

There is a *no-gain* region:

- ionization charges collected **without being multiplied** by gain layer
 - smaller signal *filtered by threshold* in the electronics
- the extent can be measured with laser in TCT

The *fill factor* must be maximized:

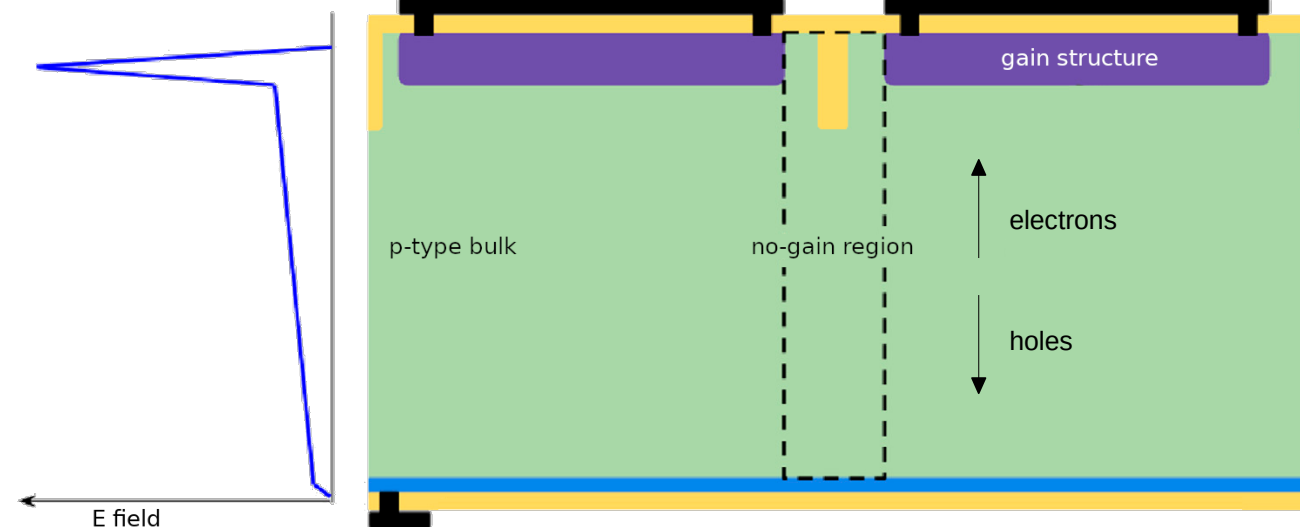
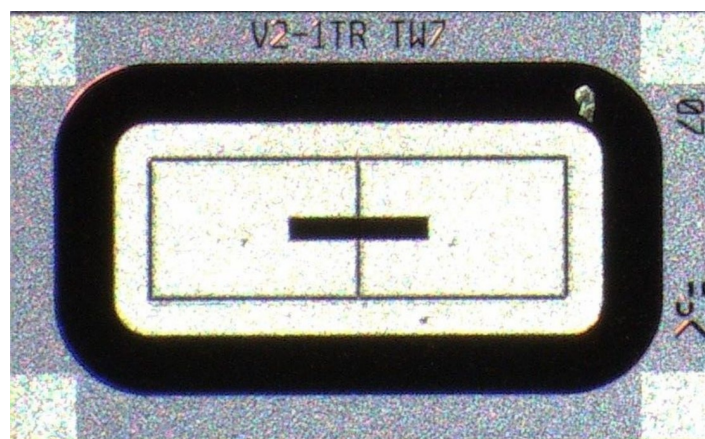
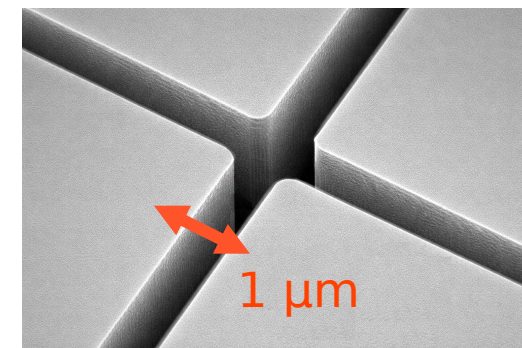
- to maximize detection efficiency
- $A_{\text{active}} / A_{\text{total}}$



New LGAD technologies: trench-isolated LGADs

Trench-isolated LGADs: trenches etched in silicon substrate and filled with SiO₂

- replace *all structures* at pixel boarder
 - no-gain region reaches **< 5 μm**
- aspect ratio of 20:1 with < 1 μm precision (DRIE)
- ▶ formation of *inversion layer* at interface
 - conductive path shorts pixels
- ▶ *defects* at Si-SiO₂ interface
 - increase in leakage current



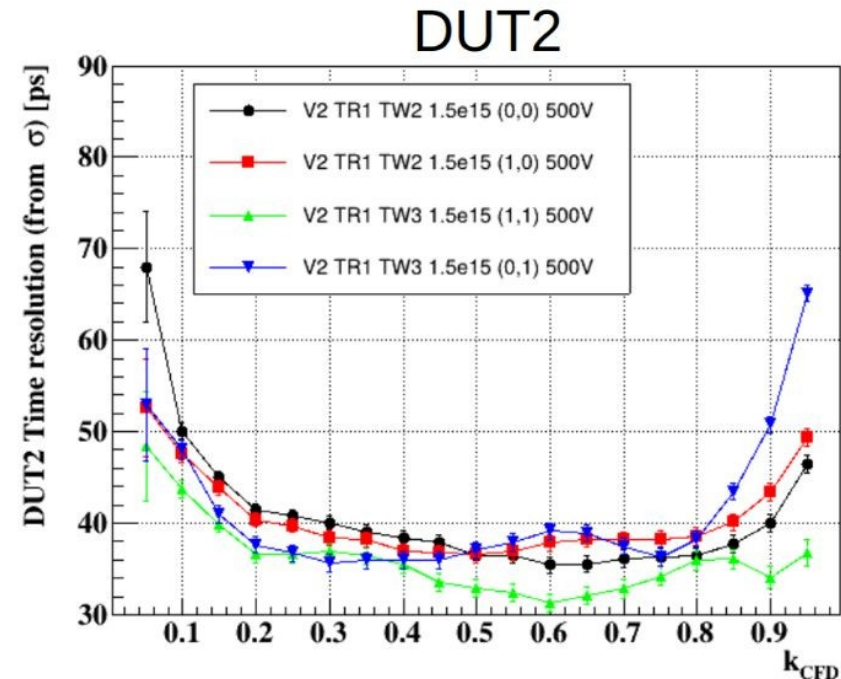
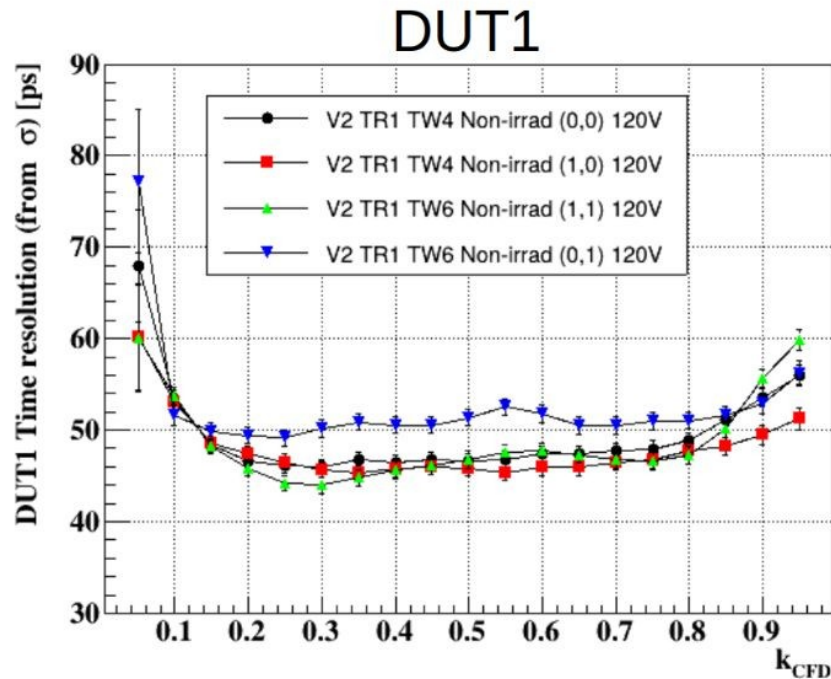
[10.1109/LED.2020.2991351]

[10.3389/fphy.2024.1359179]

New LGAD technologies: trench-isolated LGADs

Recent results:

- pitches of $375 \times 250 \mu\text{m}^2$ and $45 \mu\text{m}$ depth (FBK) with different trenches' width, depth and process
- $\sigma_t \sim \mathbf{30-45 \text{ ps}}$ measured at SPS with 120 GeV pions
 - irradiation mitigates Landau fluctuations!
- *interpad distance* (no-gain region) of **zero!**
 - for 95% (non-irradiated) and 90% ($1.5 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$) efficiency

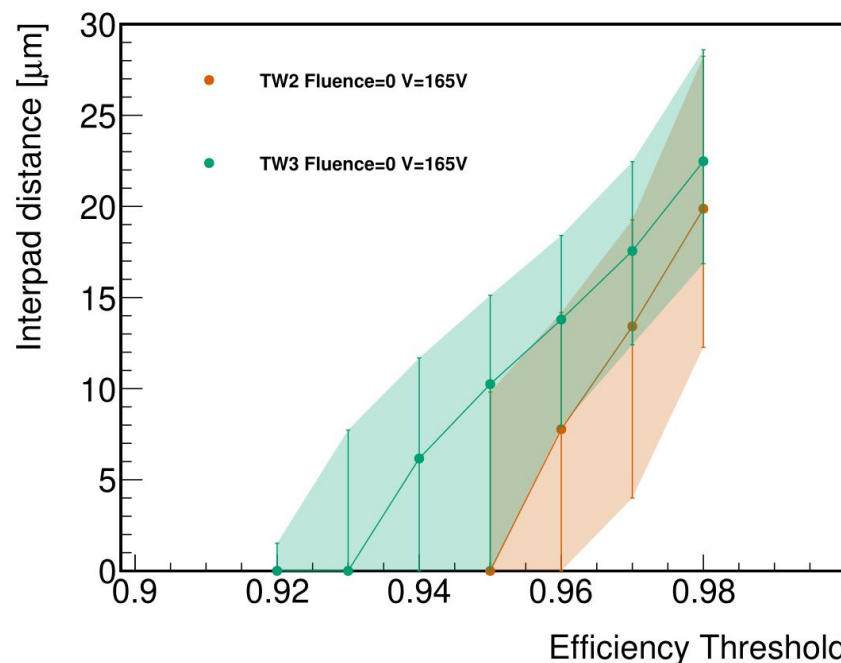
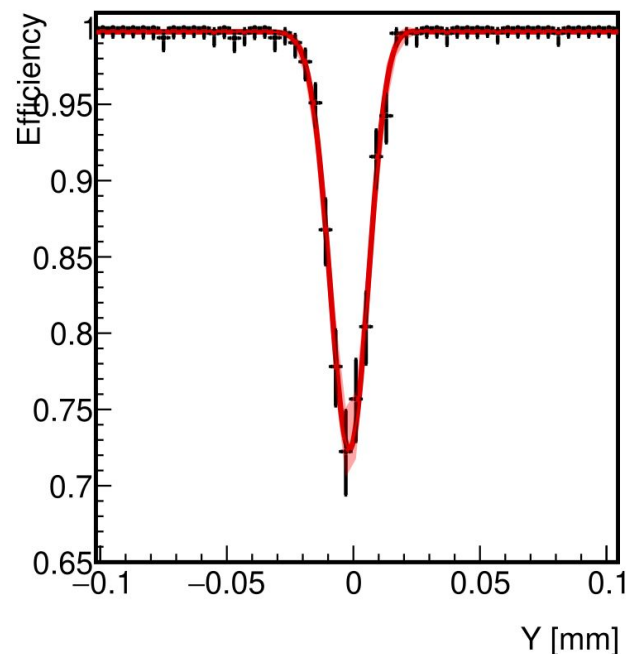


M. Fernandez, TI-LGAD Meeting

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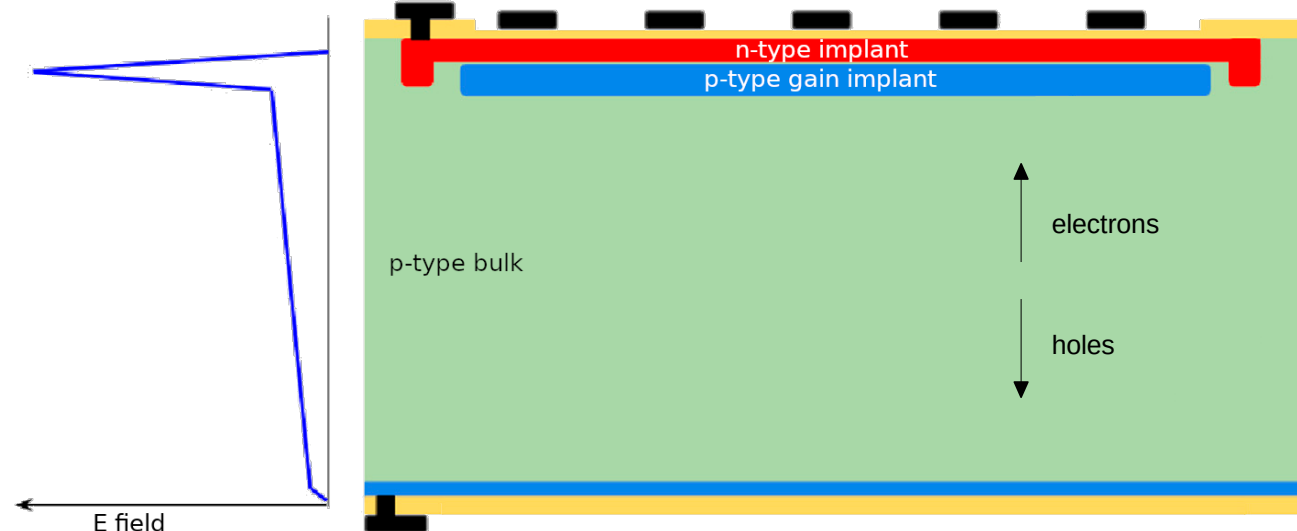
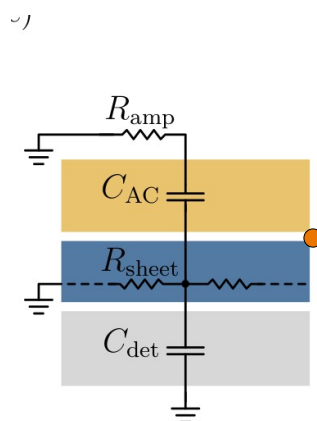
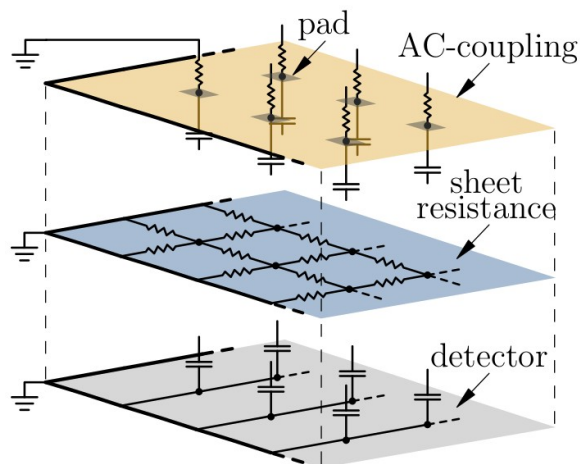


A. Carrera, TREDI21

New LGAD technologies: AC-LGAD (RSD)

Small electrodes *AC-coupled* to “one big LGAD” via thin dielectric layer:

- **continuous gain layer** → 100% fill factor by construction!
- e^- reach the n^+ layer and follow *shortest path to ground*
 - through **RC circuit** formed by n^+ layer and AC-coupled electrodes
 - the closer the electrode to hit-position, the lower the resistivity → e^- *split proportionally*
 - e^- *discharged* in the peripheral DC path to ground (with JTE)
- large **charge sharing** between readout electrodes
 - enhanced spatial resolution

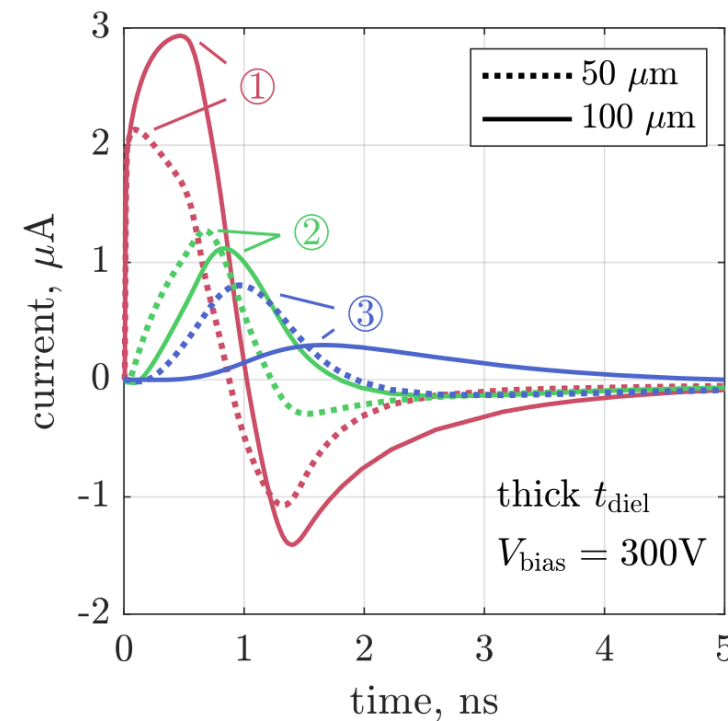
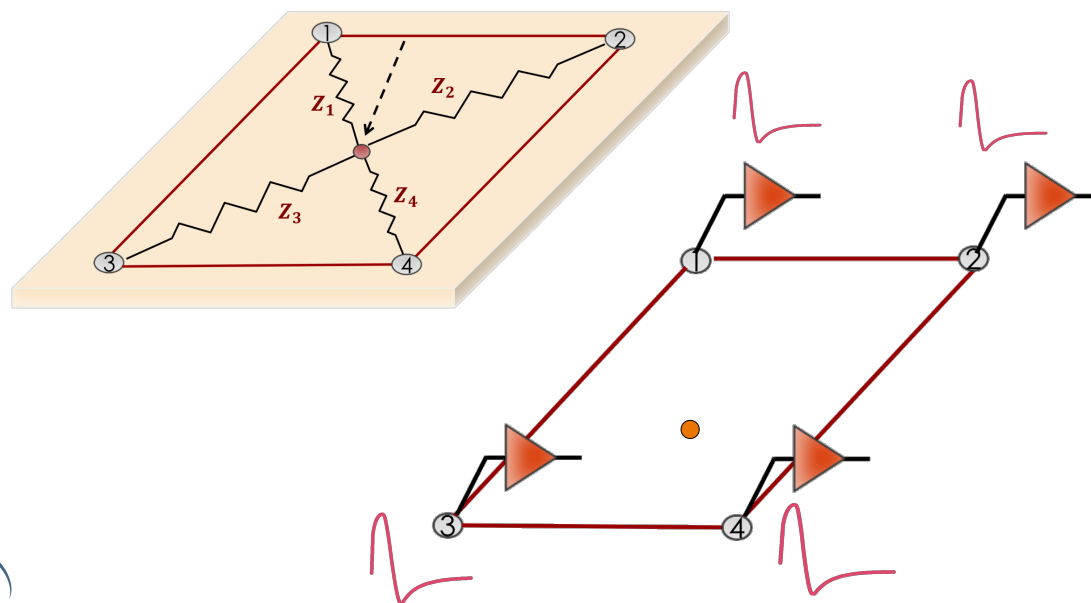


[10.3389/fphy.2024.1359179]

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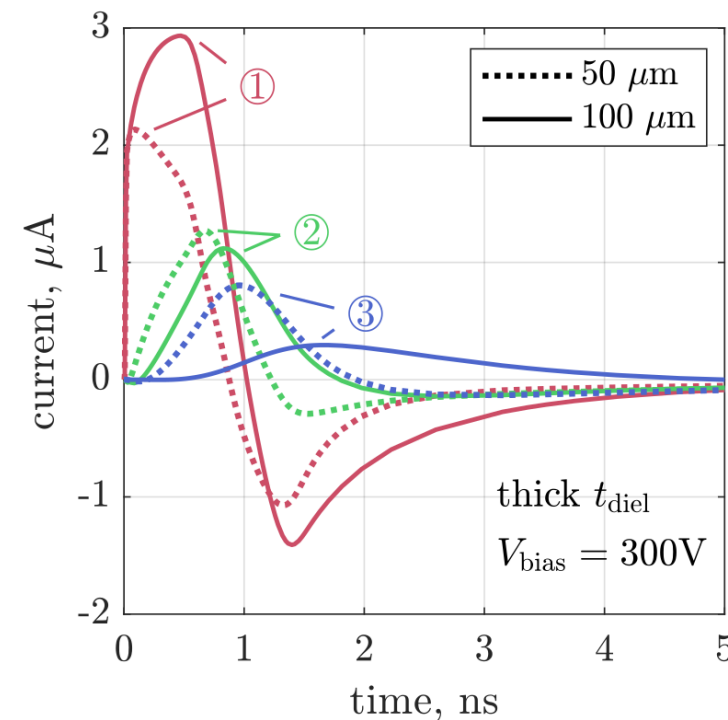
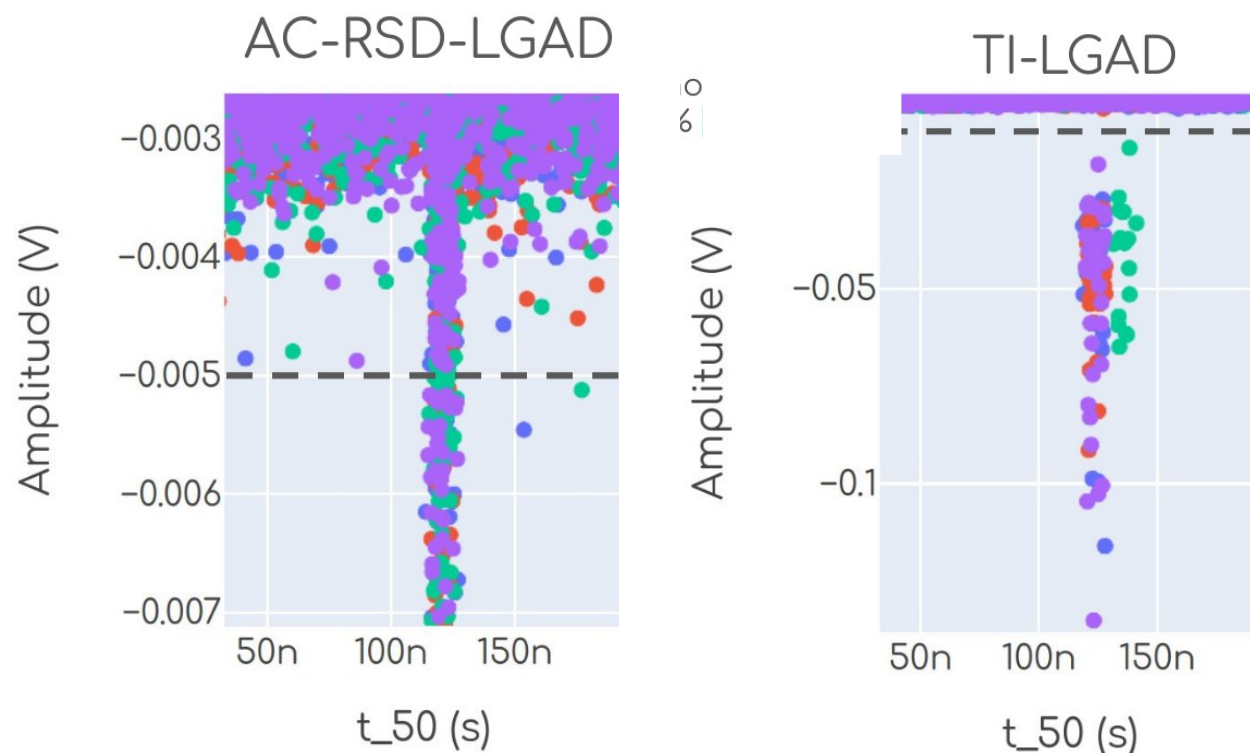


[10.1016/j.nima.2020.163479]

New LGAD technologies: AC-LGAD (RSD)

The **signal**:

- ▶ propagation of $O(100 \mu\text{m})$ before collection \rightarrow signal spreading to a minimum of *four* electrodes
- ▶ baseline fluctuations (pile-up)
- ▶ bipolar signal \rightarrow not compatible with charge-integrating electronics (photon science)

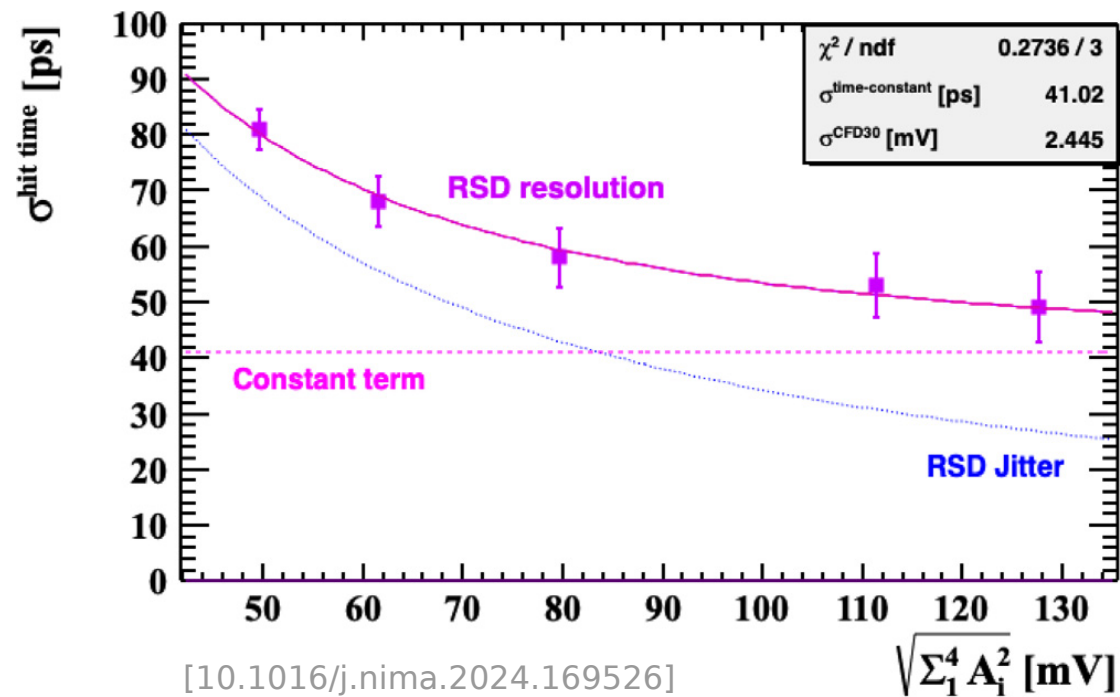
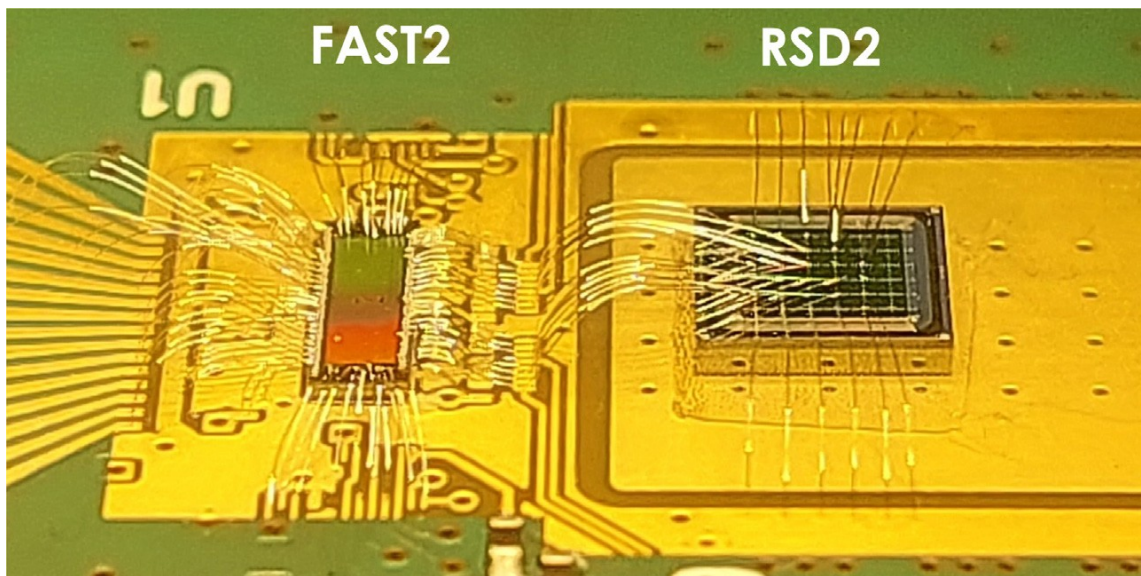


[10.1016/j.nima.2020.163479]

New LGAD technologies: AC-LGAD (RSD)

Recent results:

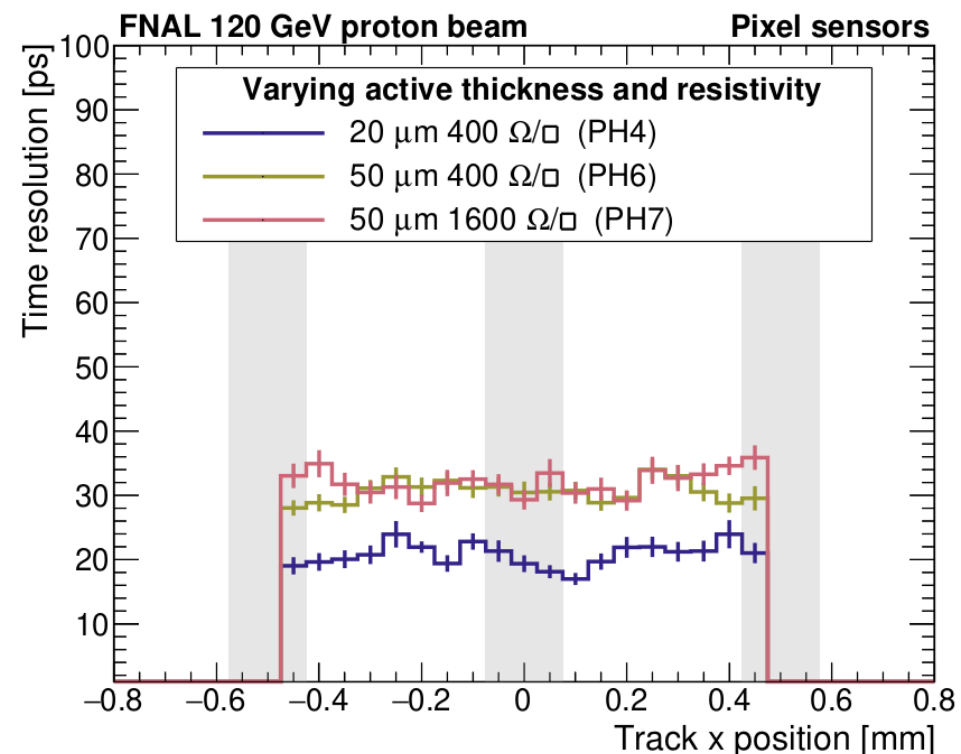
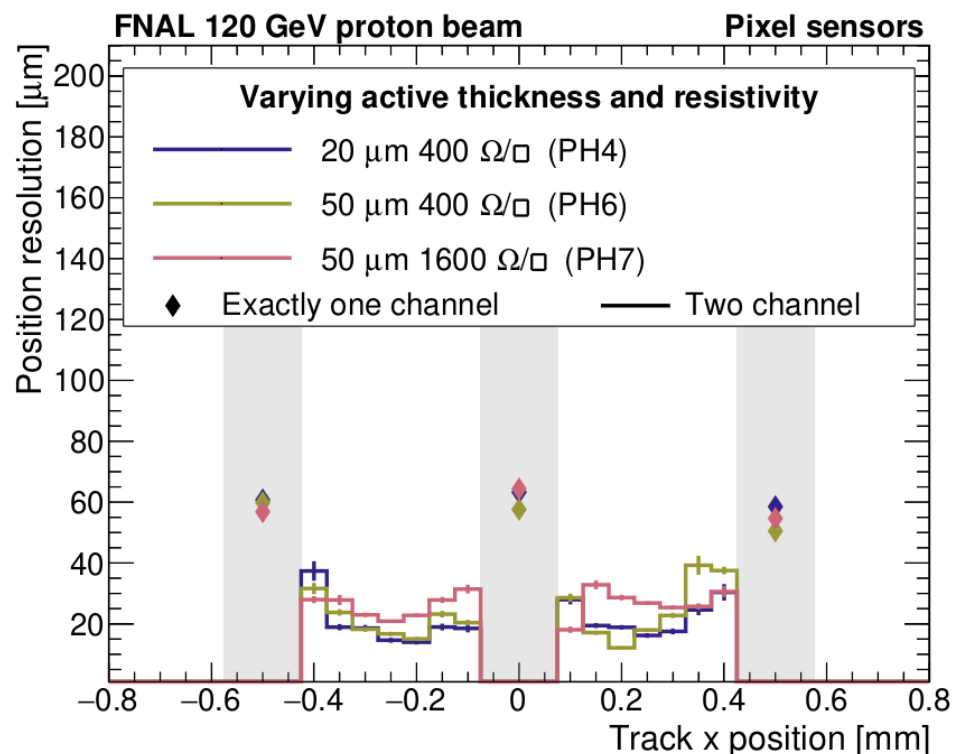
- pitch 450 μm and active volume of **55 μm** with cross-shaped electrodes (FBK)
 - readout with FAST2 ASIC tested at DESY with 5 GeV e^- beam
 - spatial resolution of **$14 \pm 1 \mu\text{m}$** (3.4% pitch) and **$\sigma_t \sim 49 \pm 6 \text{ ps}$**



New LGAD technologies: AC-LGAD (RSD)

Recent results:

- pitch 500 μm , thinner active volumes (e.g. **20 μm**), square electrodes (HPK) and varying resistivity
- readout with FNAL/UCSC boards and tested at FNAL with 120 GeV proton beam
 - spatial resolution of **21 μm** and $\sigma_t \sim$ **20 ps**



[10.48550/arXiv.2407.09928]

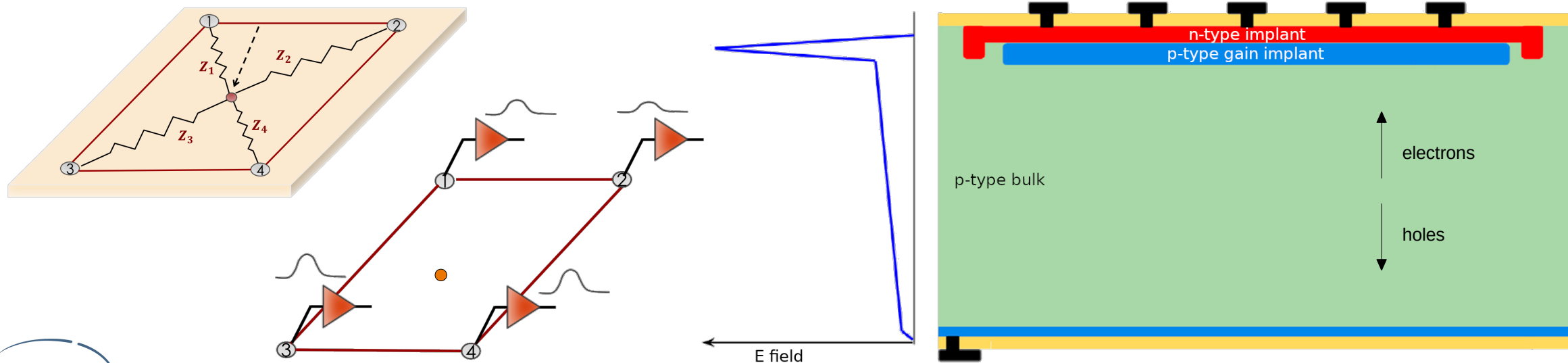
New LGAD technologies: DC-LGAD (RSD)

To avoid the **signal spreading** of AC-LGADs → DC-LGADs:

- *removed dielectric* between electrodes and n⁺ layer → **ohmic contact**
- **electric isolation** of pixels via *high sheet resistance* of n⁺ layer and optimization of *inter-pads distance*

The **signal**:

- is fully contained (well controlled charge sharing) → scalable to larger devices
- unipolar and absence of baseline fluctuations
- ▶ non-uniform resolution across sensor area



New LGAD technologies: DC-LGAD (RSD)

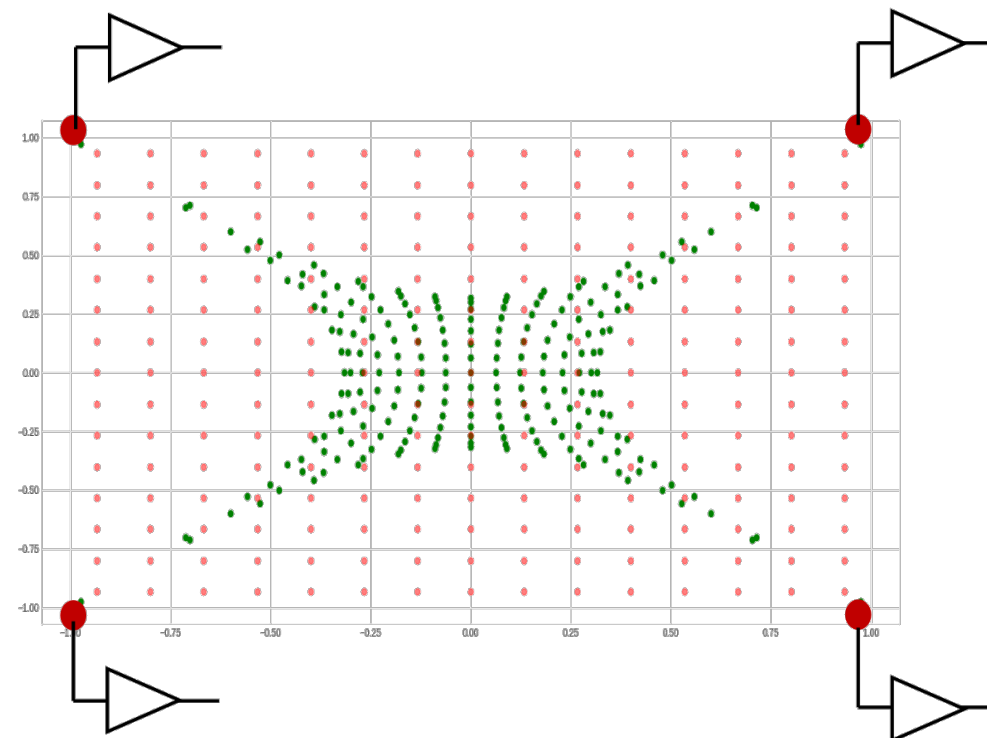
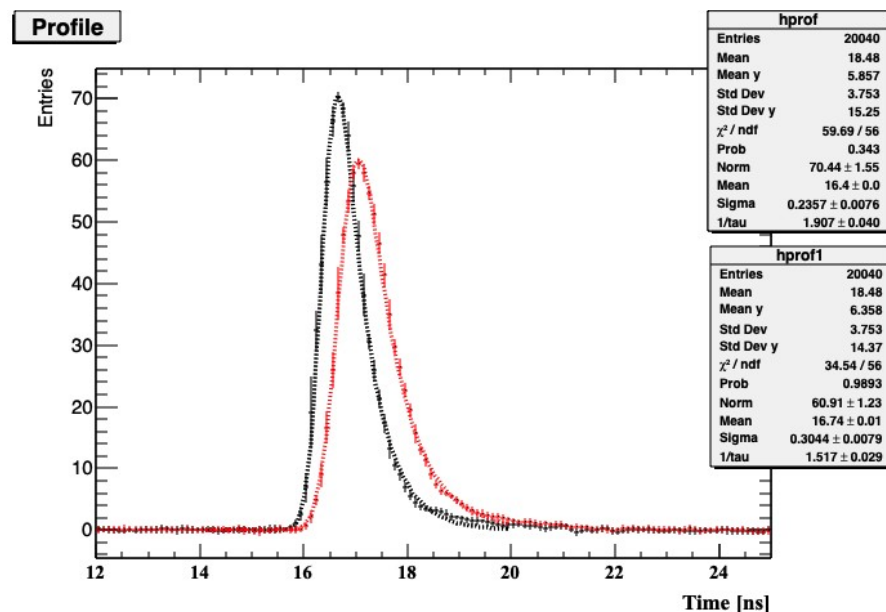
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[10.1016/j.nima.2022.167815]



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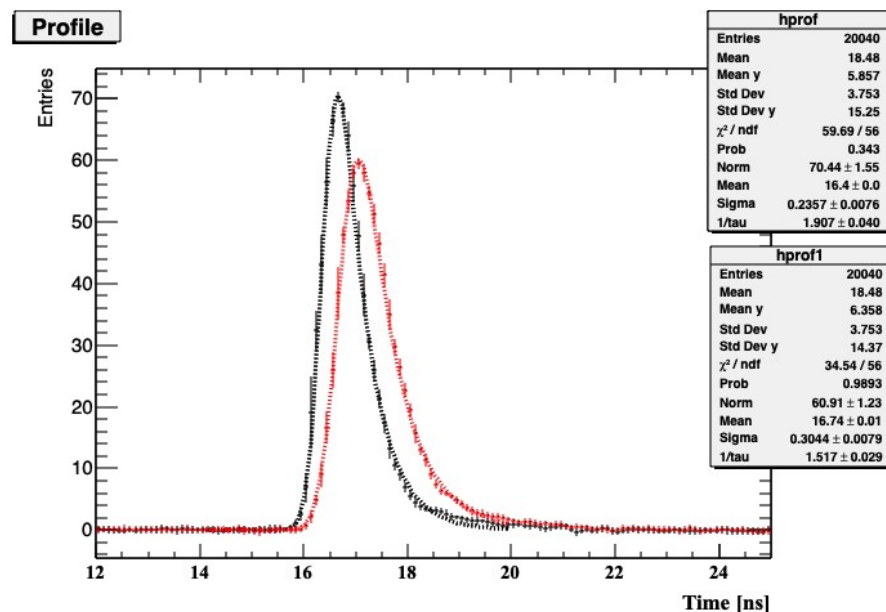
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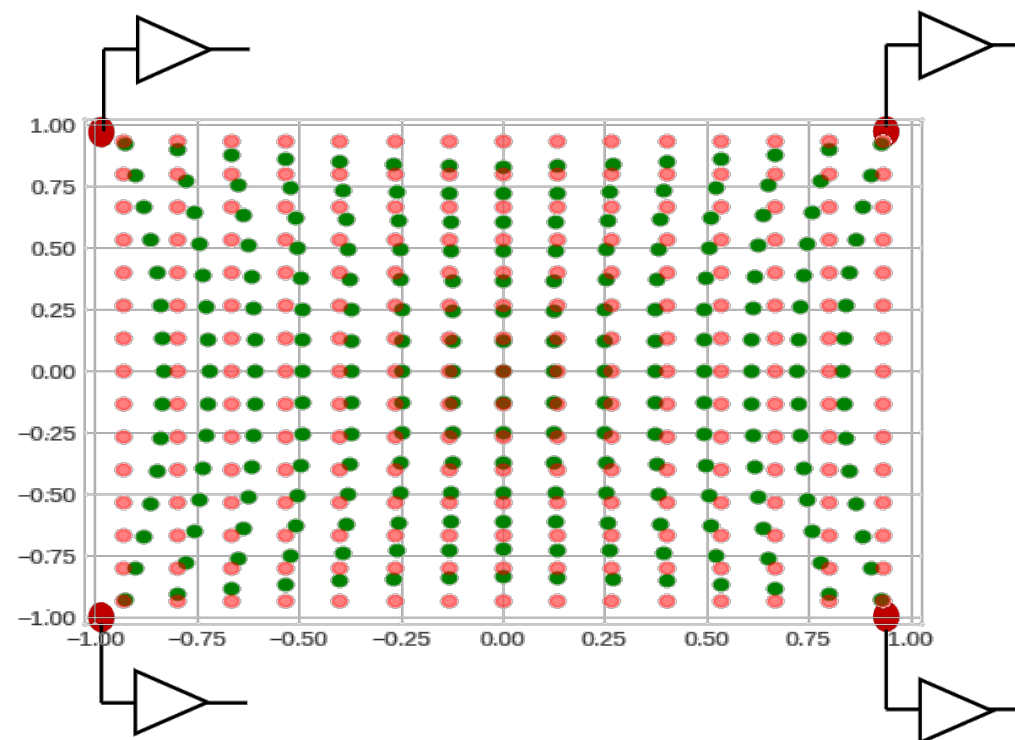
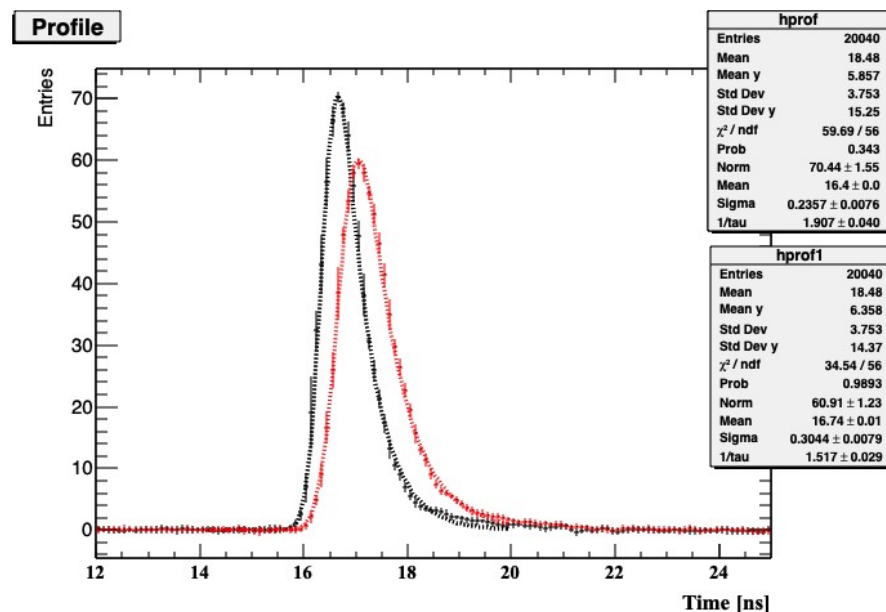
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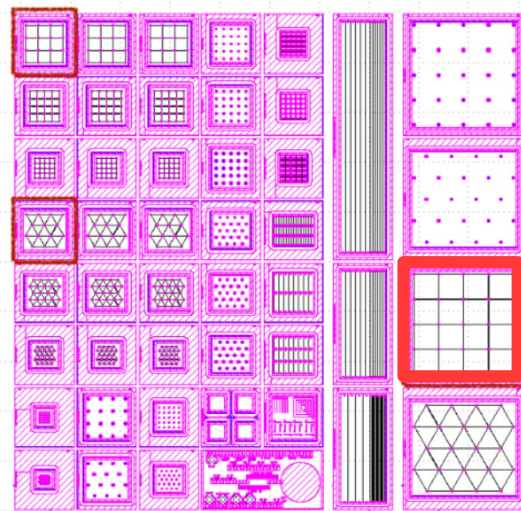
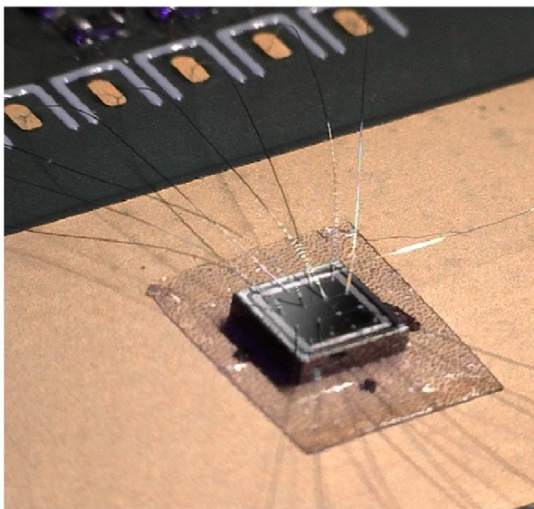


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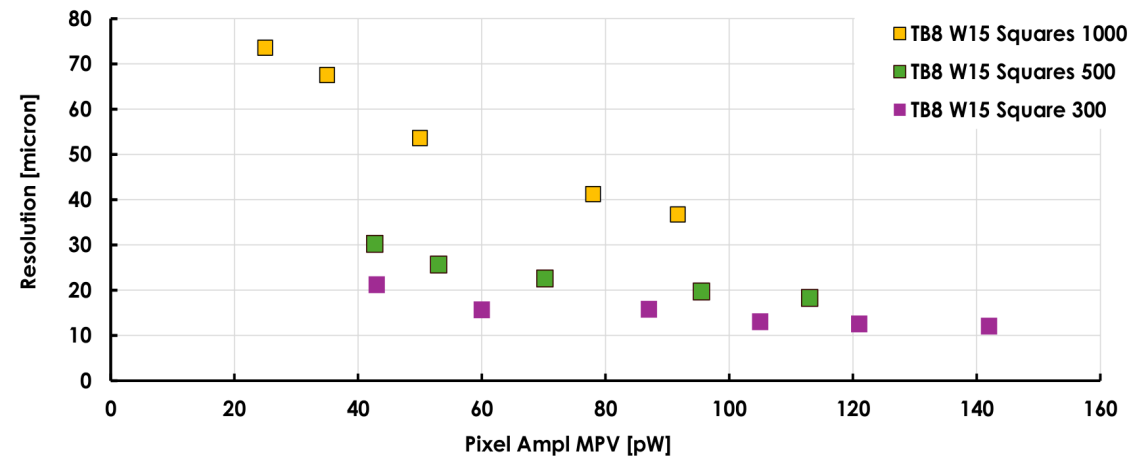
Recent results:

- test beam in DESY with 5.2 GeV e⁻
 - thickness of **55 μm** and pitches of 300, 500 and 1000 μm
 - low resistivity and square electrodes
 - read out by FNAL board
- **$\sigma_t \sim 40$ ps** doesn't depend on pitch!
- spatial resolution does, reaching **10 μm**

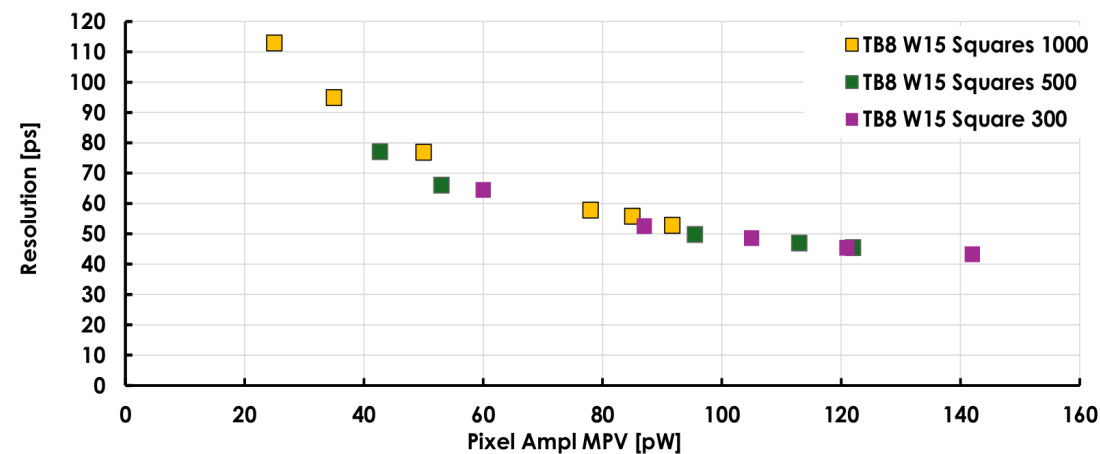
[10.1016/j.nima.2025.170796]



Spatial Resolution



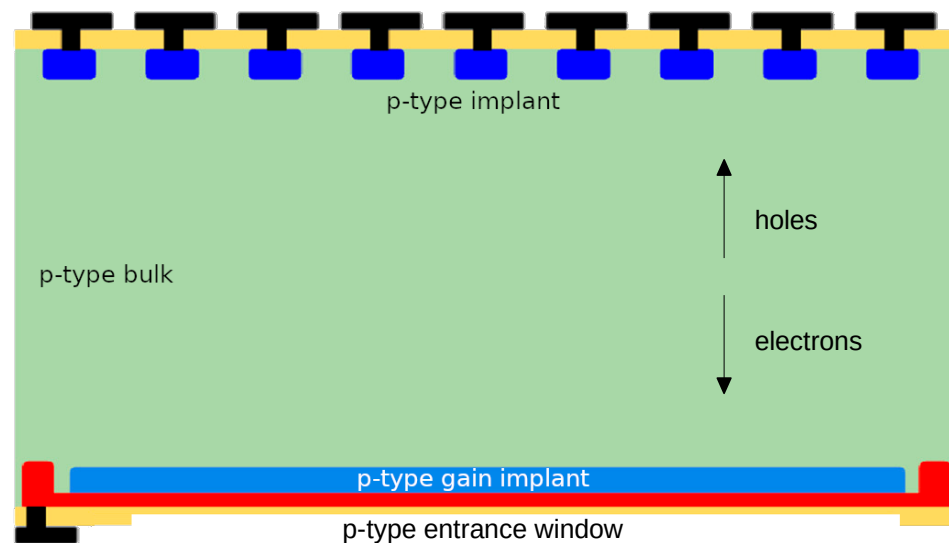
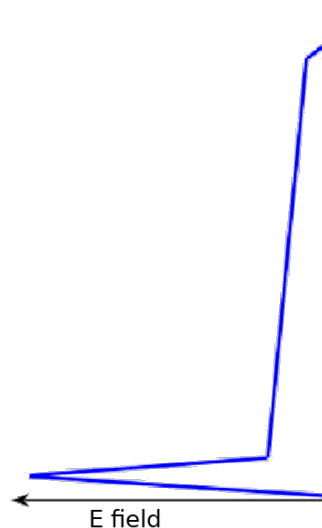
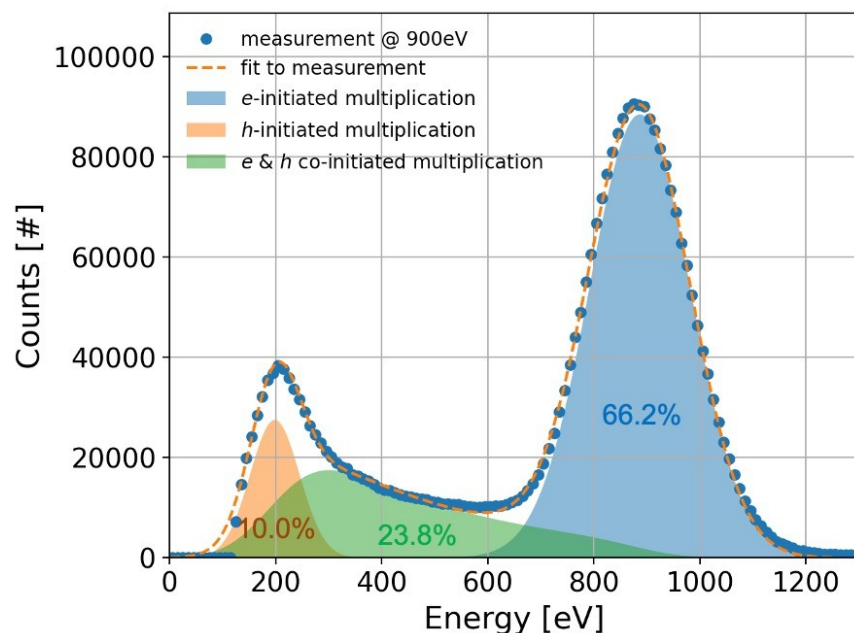
Temporal Resolution



New LGAD technologies: inverted LGAD (i-LGAD)

Continuous gain layer at **backside** and **split p⁺⁺** electrodes:

- 100% fill factor by construction!
- gain layer at backside → soft x-rays (few μm penetration)
- signals with opposite polarity (positive)
 - p⁺⁺ on p technology collects holes
- ▶ complicated production for backside processing → thicker sensors = worse timing



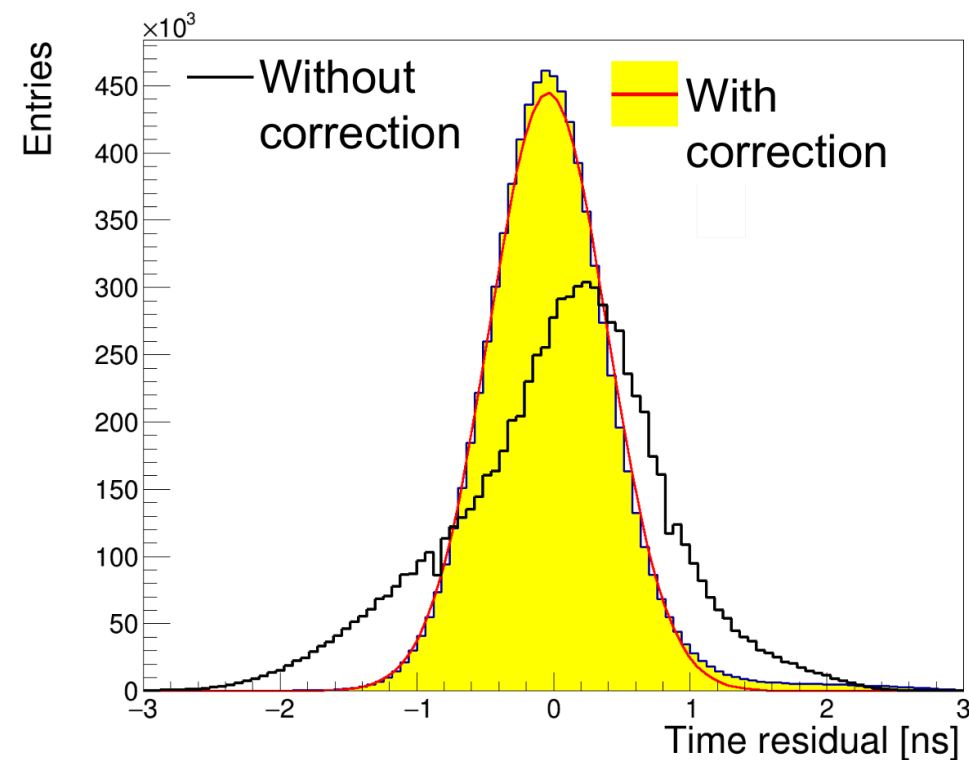
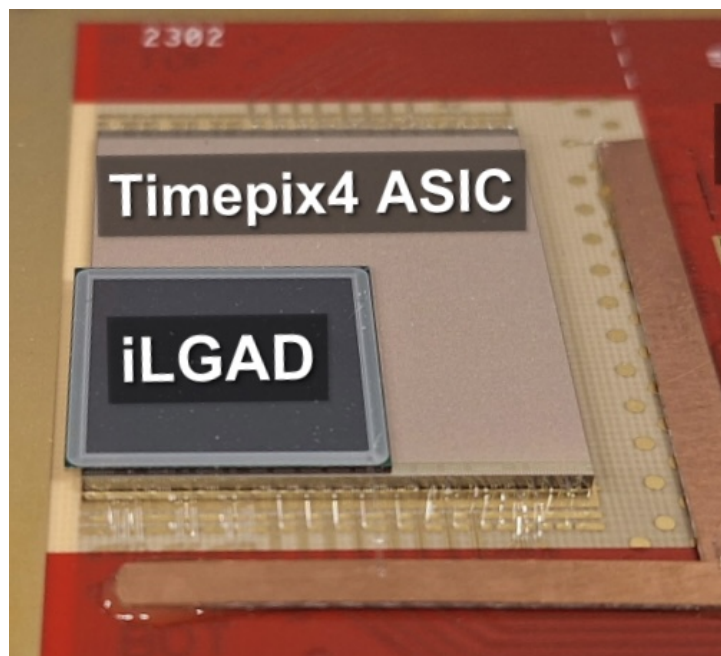
[10.3389/fphy.2024.1359179]

New LGAD technologies: inverted LGAD (i-LGAD)

Recent results:

- thickness of **250 μm** with pitches of 55 μm (Micron Semiconductors)
 - paired to Timepix4 readout board and tested with 180 GeV/c hadron beam
- approach aimed at achieving high spatial resolution **$\sim 4.3 \mu\text{m}$**
- $\sigma_t \sim \mathbf{358 \text{ ps}}$ (with time-walk corrections)

[arXiv:2509.09308]



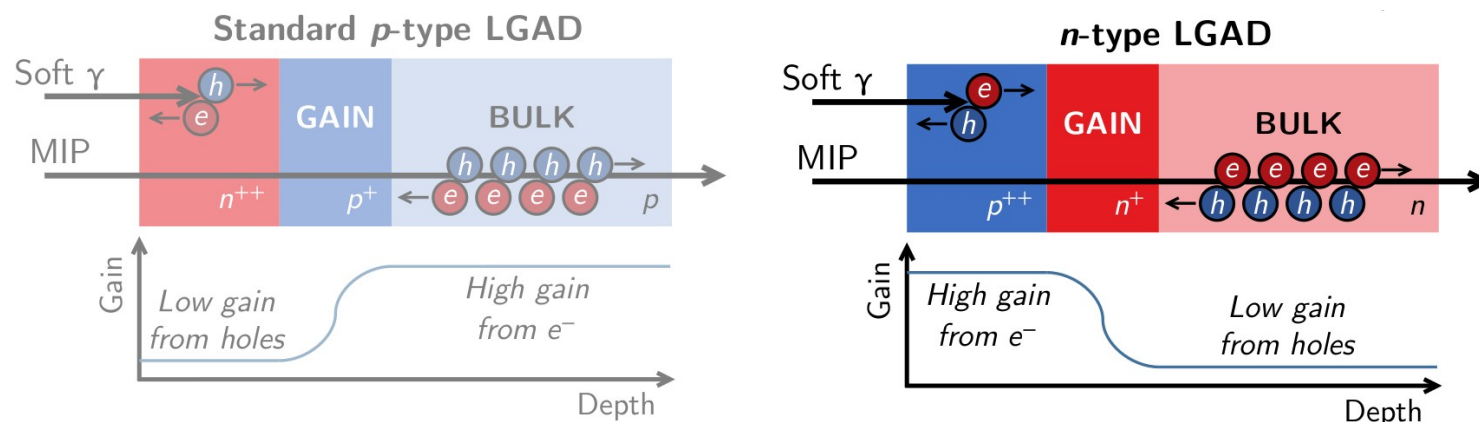
New LGAD technologies: nLGAD

New technology for **soft x-ray** detection (< 1 keV):

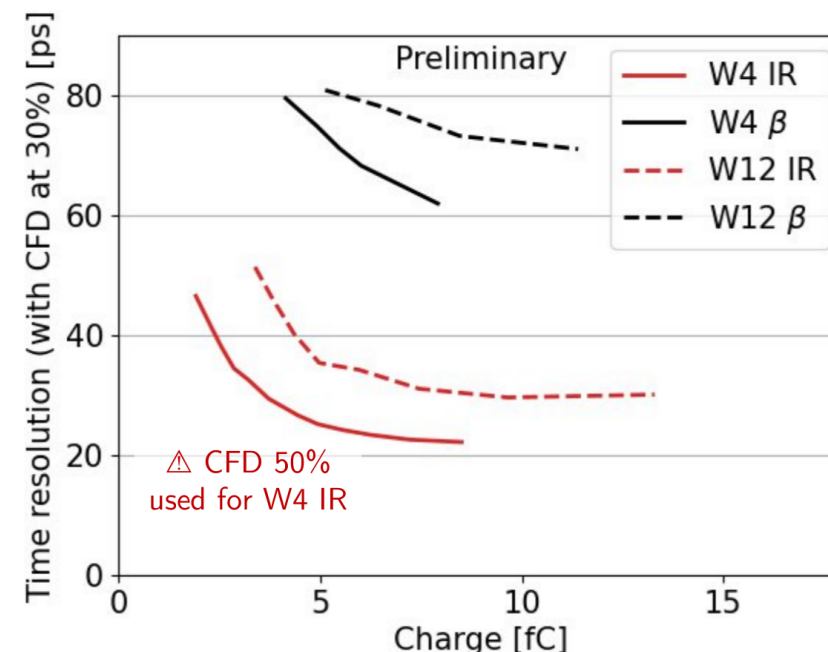
- gain depends on *species triggering avalanche* and is **higher for e^-**
- *inverted doping* with respect to standard LGADs (also for i-LGADs)

Recent results:

- thickness of **55 μm** with 1.3 mm pitch (FBK)
 - readout with 4 GHz oscilloscope
- time resolution with β particles of **62 ps**



[L. Massaccesi, TREDI21]



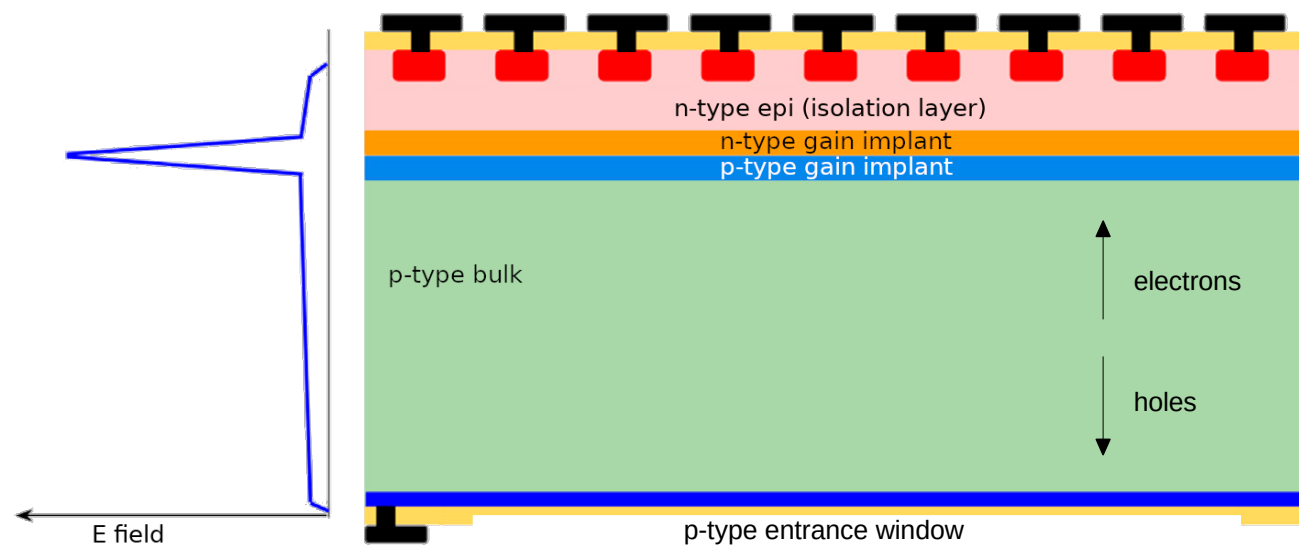
New LGAD technologies: deep-junction LGAD

Very new technology, only recently fabricated:

- larger window for photo-detection
- ▶ p-n junction buried **5 μm** into bulk \rightarrow 100% fill factor, but non standard process
 - 1) implantation of gain layers on different wafers, then w-w bonding and thinning
 - 2) p-type substrate with gain implants close to surface plus epitaxial growth of n-type layer
- small pixels segmentation by creation of n^+ *contacts* separated by p-stop rings

Recent results:

- not tested yet!



[10.3389/fphy.2024.1359179]

Conclusions

That's a **LOT** of LGAD designs.

- you made it to the end of this presentation (*excellent*)
- ▶ you probably won't remember everything...
- ...so you can look at this table!

LGAD design	thickness [μm]	σ_t [ps]	σ_{hit} [μm]	link
standard	50	25	-	arXiv:2512.01855
trench-isolated	45	30	-	M. Fernandez, TI-LGAD Meeting
AC-LGAD	20	20	21	10.48550/arXiv.2407.09928
DC-LGAD	55	40	10	10.1016/j.nima.2025.170796
I-LGAD	250	358	4.3	arXiv:2509.09308
N-LGAD	55	62	-	L. Massaccesi, TREDI21
DJ-LGAD	-	-	-	F. Capocasa, TREDI21

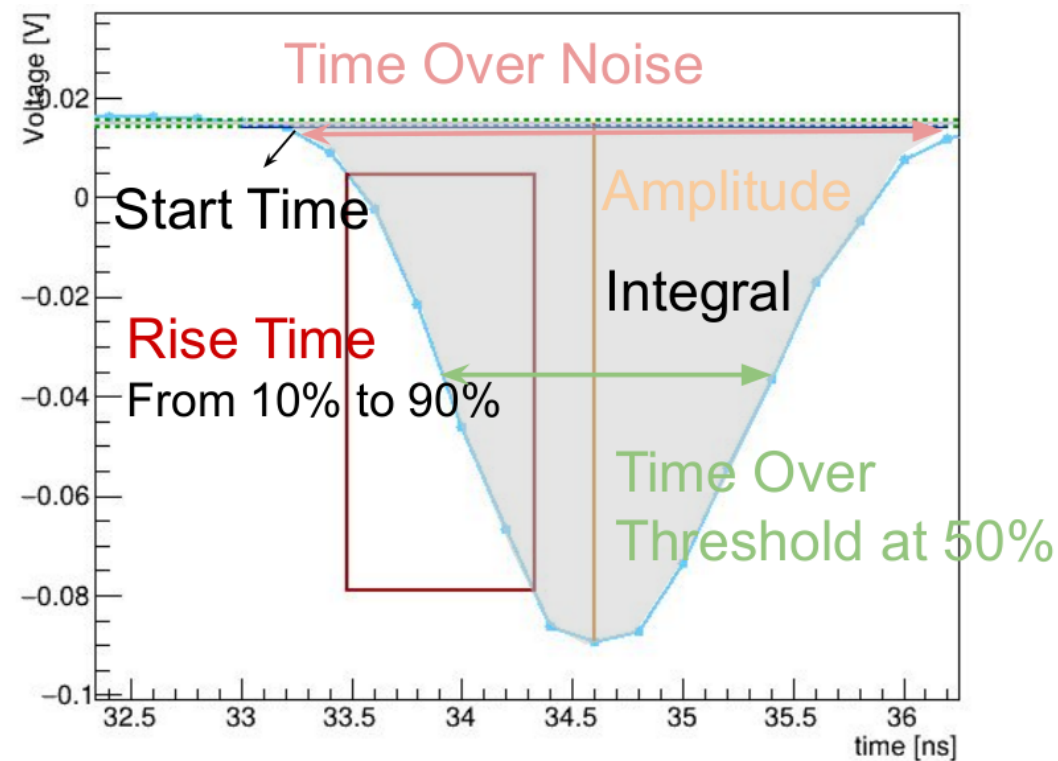
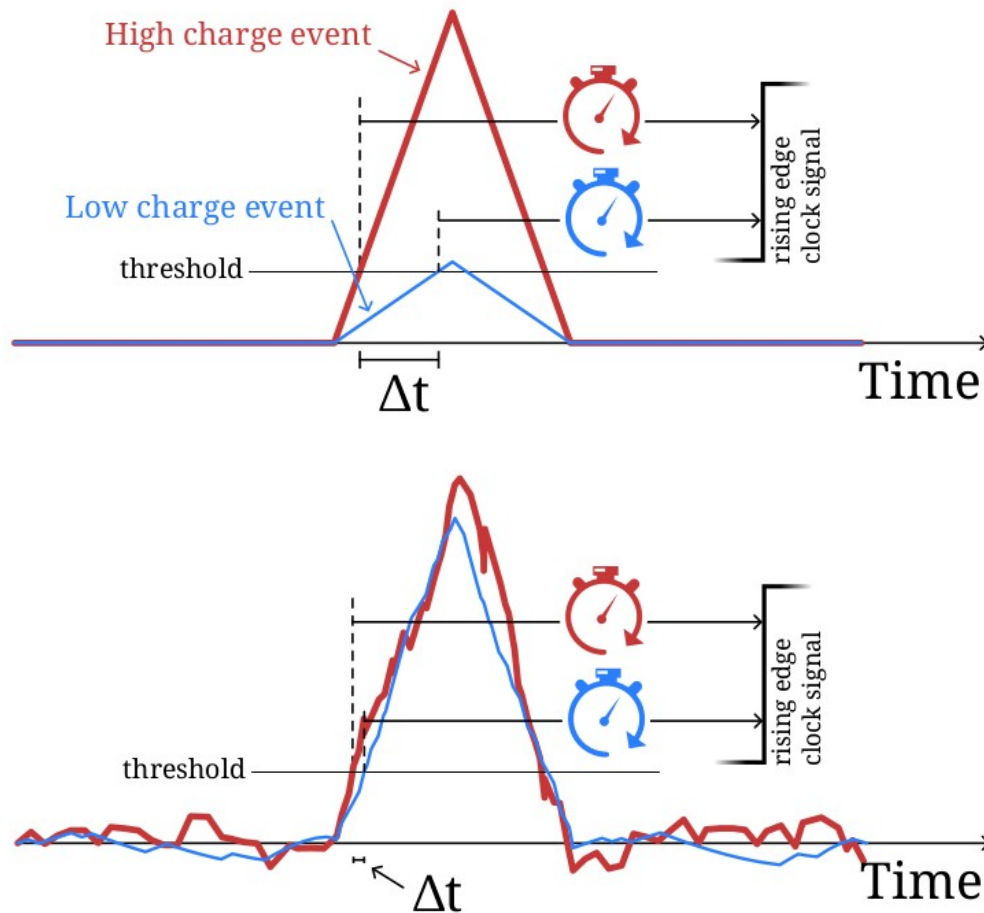
Thank you for your attention!

Backup

kCFD: constant fraction discrimination

Technique used to map big and large signals to a common reference shape:

- reduce impact of Landau noise



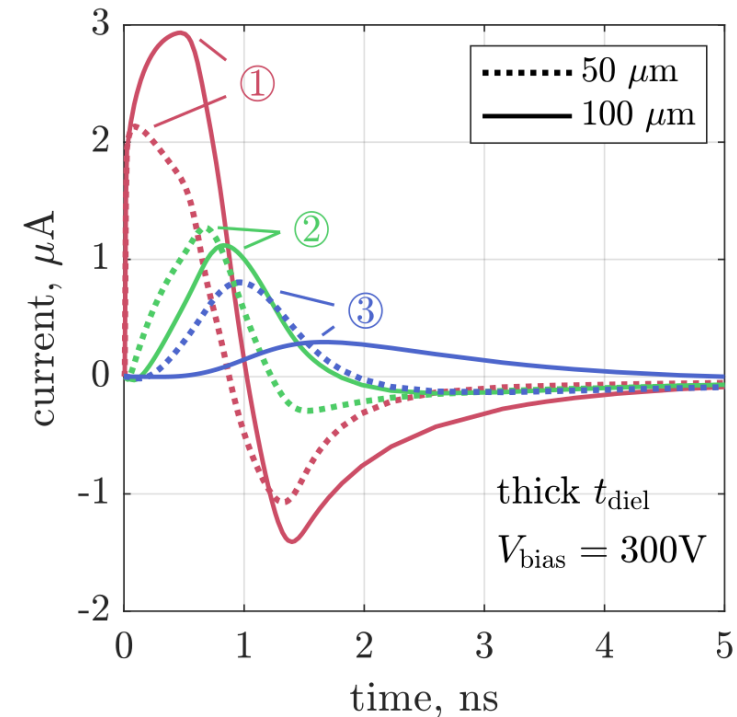
New LGAD technologies: AC-LGAD (RSD)

The **signal**:

- ▶ propagation of $O(100 \mu\text{m})$ before collection \rightarrow signal spreading to a minimum of *four* electrodes
- ▶ baseline fluctuations (pile-up)
- ▶ bipolar signal \rightarrow not compatible with charge-integrating electronics (photon science)

Signal **shape**:

- *positive lobe*: current lateral spread
 - lossy transmission line (n^+ layer/bulk/AC-pads)
- *negative lobe*: AC-pad RC discharge
 - $R \rightarrow$ read-out input resistance, the n^+ sheet resistance
 - $C \rightarrow$ capacitance towards sensor backside and metal pad
 - large RC = larger signal (good) and discharge time (bad)

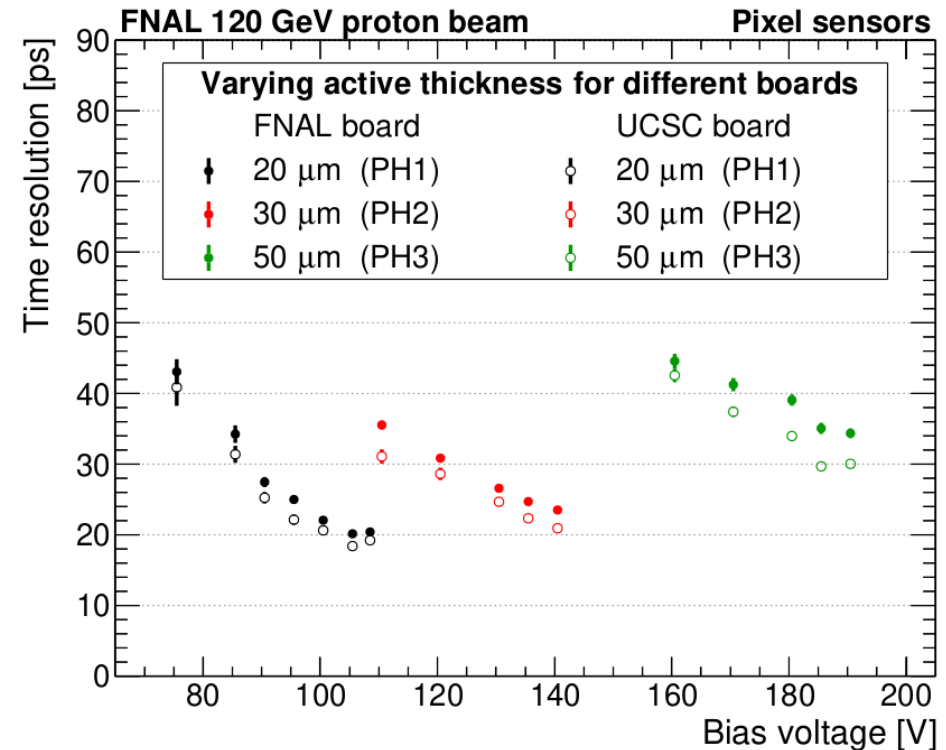
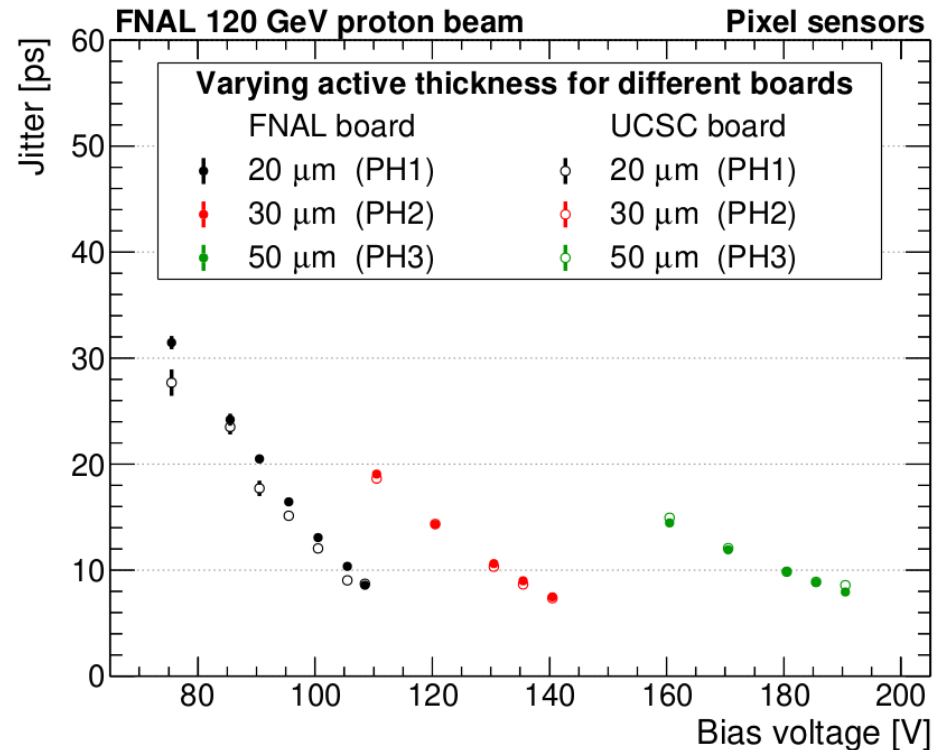


[10.1016/j.nima.2020.163479]

New LGAD technologies: AC-LGAD (RSD)

Recent results:

- pitch 500 μm , thinner active volumes (e.g. **20 μm**), square electrodes (HPK) and varying resistivity
- readout with FNAL/UCSC boards and tested at FNAL with 120 GeV proton beam
 - spatial resolution of **21 μm** and $\sigma_t \sim$ **20 ps**

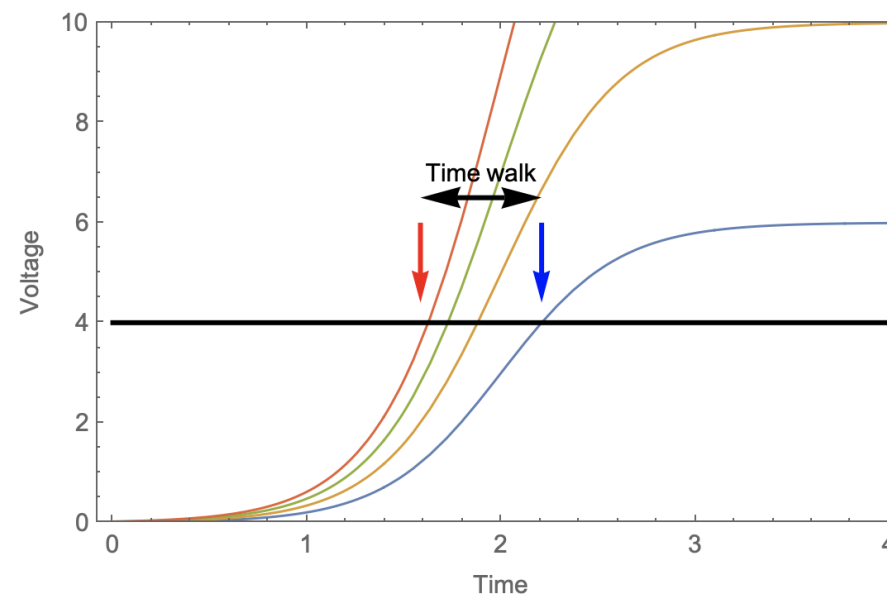
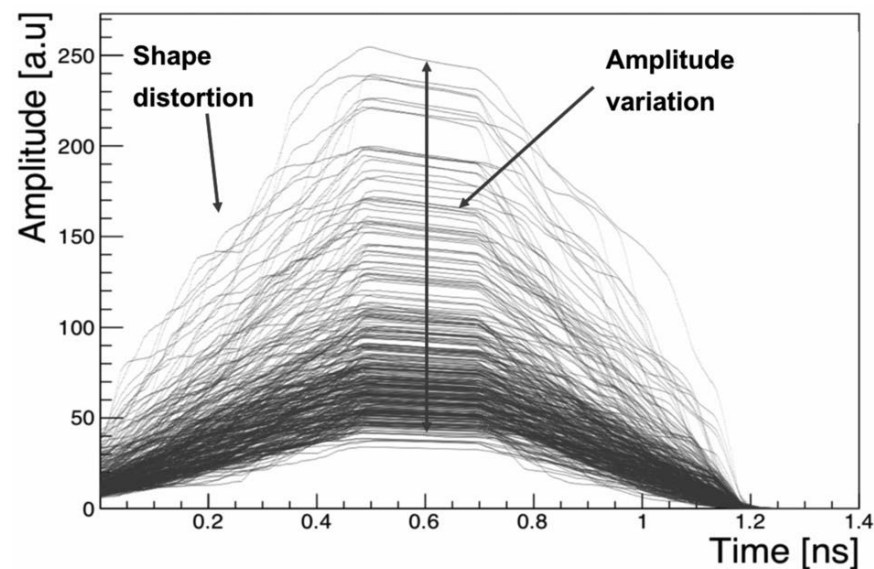


[10.48550/arXiv.2407.09928]

Another problem: noise sources

Most important factors contributing to temporal resolution σ_t :

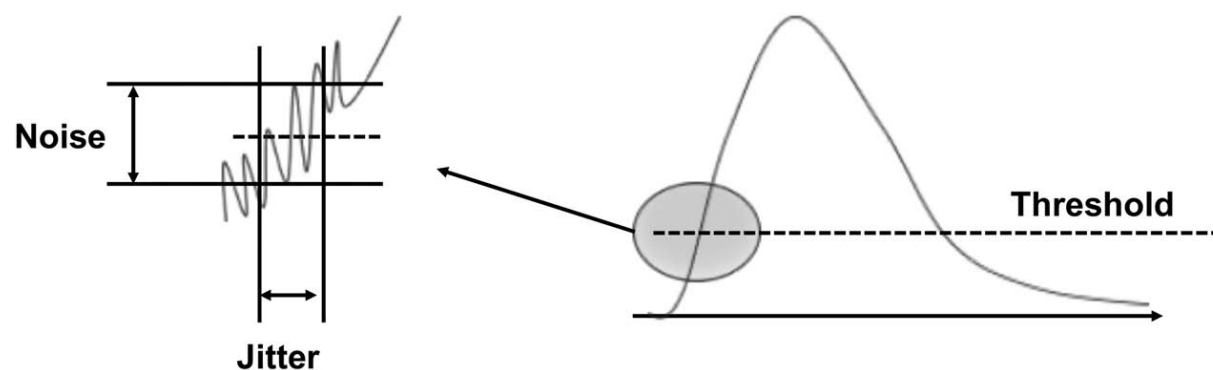
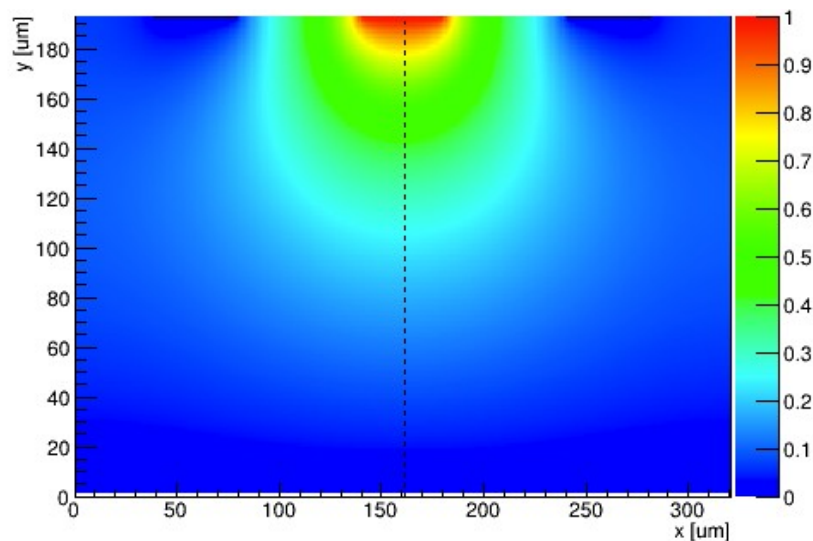
- $\sigma_t^2 = \sigma_{\text{jitter}}^2 + \sigma_{\text{Landau}}^2 + \sigma_{\text{time-walk}}^2 + \sigma_{\text{distortion}}^2 + \sigma_{\text{TDC}}^2$
 - σ_{Landau} and $\sigma_{\text{time-walk}}$: non-uniform energy deposition by impinging particles
 - σ_{jitter} : electronic noise
 - $\sigma_{\text{distortion}}$: non-saturated drift velocity (non-uniform weighting field) \rightarrow negligible
 - σ_{TDC} : finite size of TDC bins



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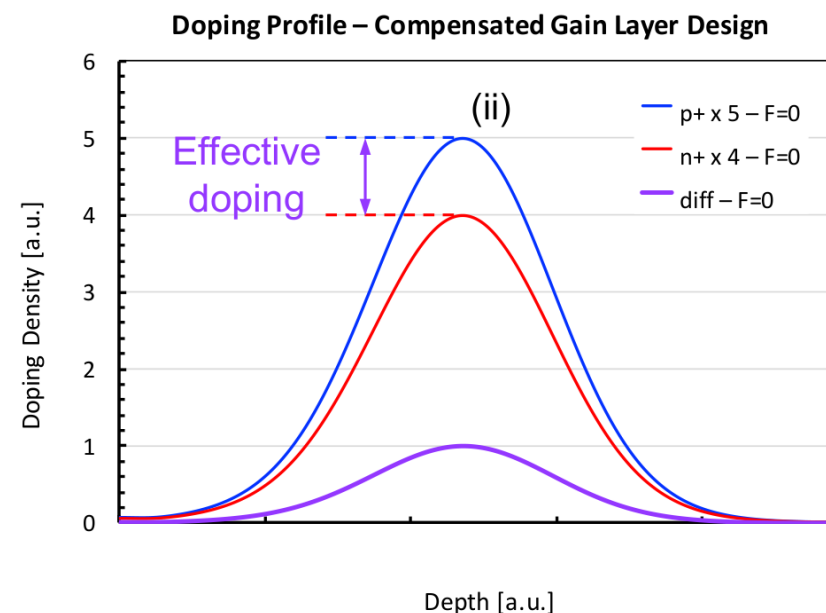
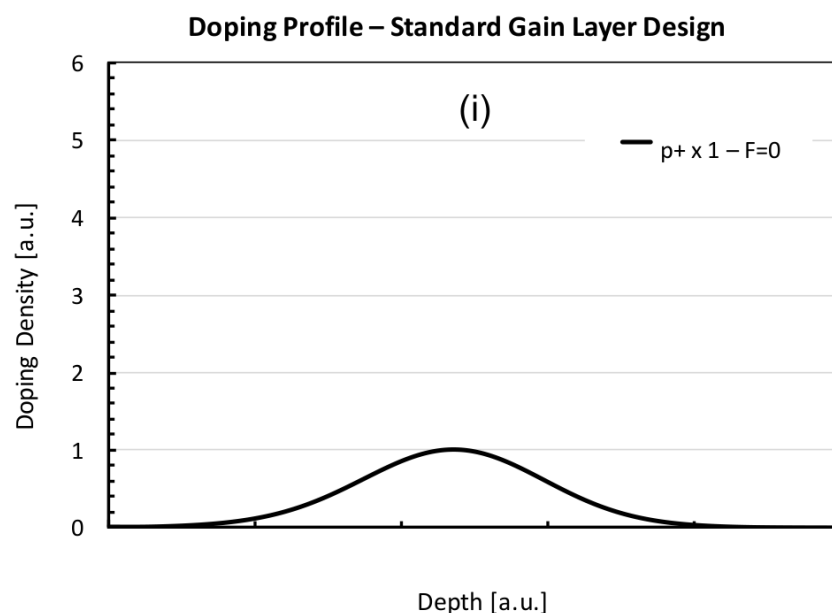
Yet another problem: radiation hardness

Irradiation causes three main defects:

- decreased charge collection efficiency, increased leakage current and change of doping profiles

The p⁺ gain implant is doped with acceptors → deactivated by boron deactivation:

- no gain at a fluence of circa $10^{16} \text{ n}_{\text{eq}} \text{ cm}^{-2}$ circa
- defect engineering: acceptors (boron, indium, gallium) co-implanted with carbon
- compensation of p⁺ and n⁺ dopants



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